

CrSBr: doping and magnetic control

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Outline

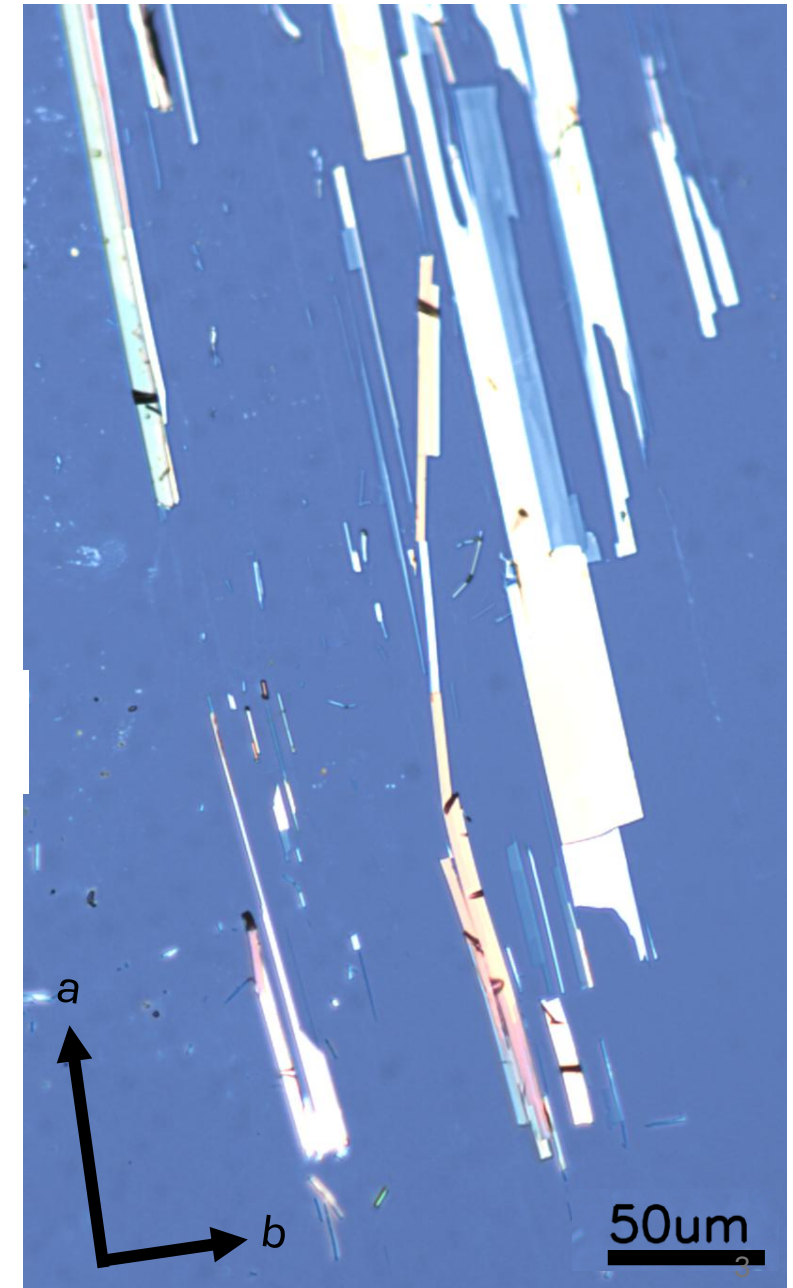
Motivation

Optical measurements

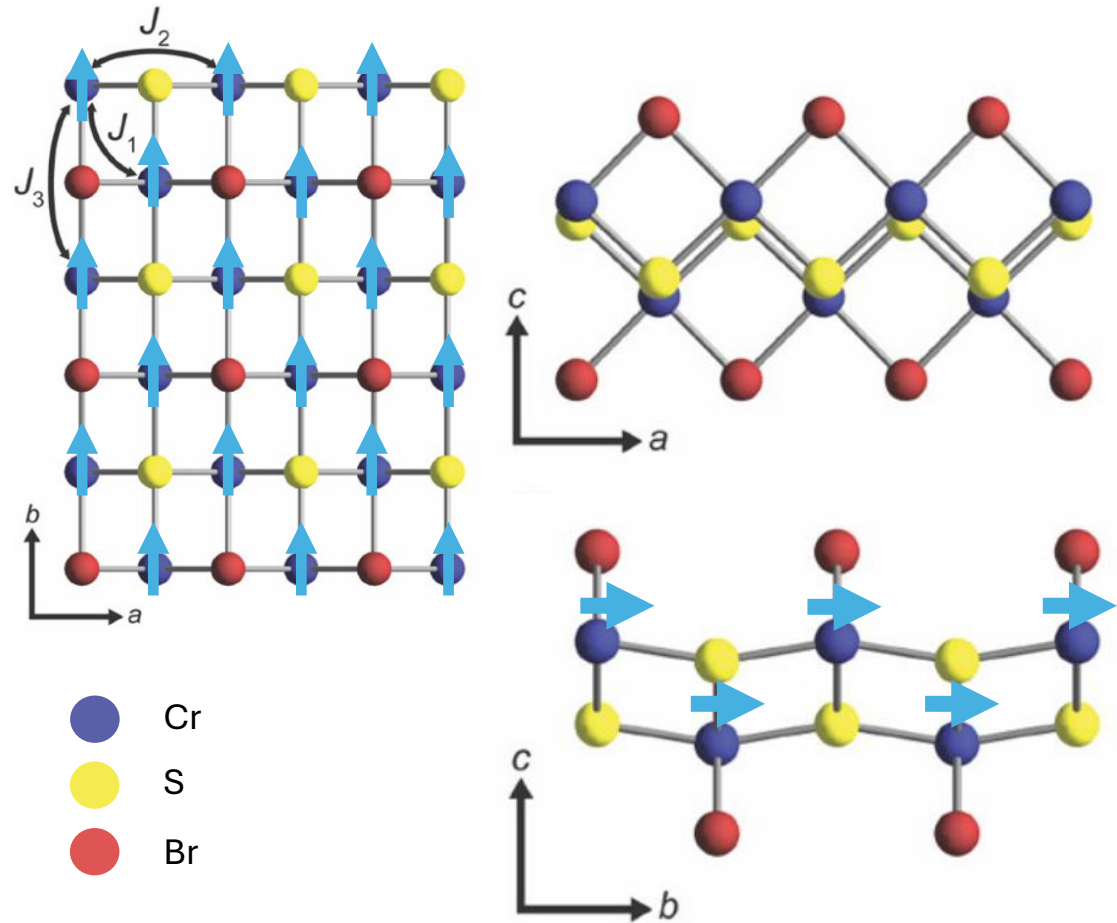
Conclusions and outlook

Properties of CrSBr

- 2D material
- Direct gap semiconductor
- A-type antiferromagnet
- Strong light-matter coupling
- Highly anisotropic



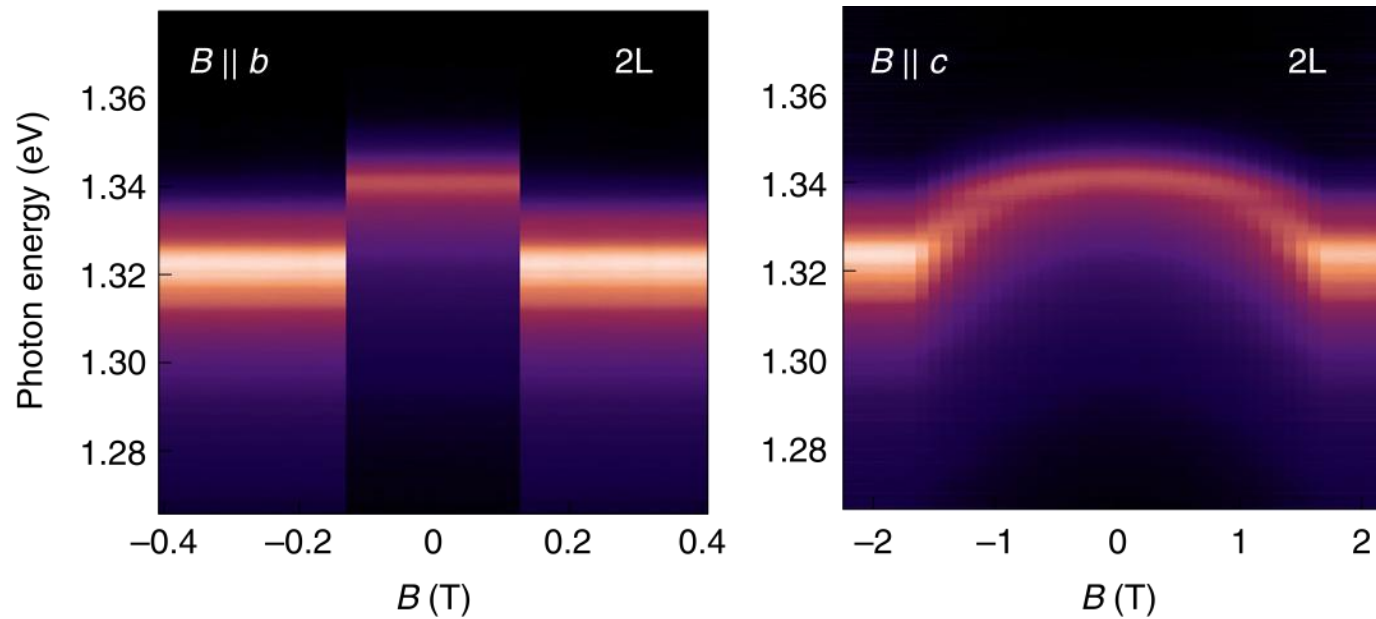
Properties of CrSBr: magnetism



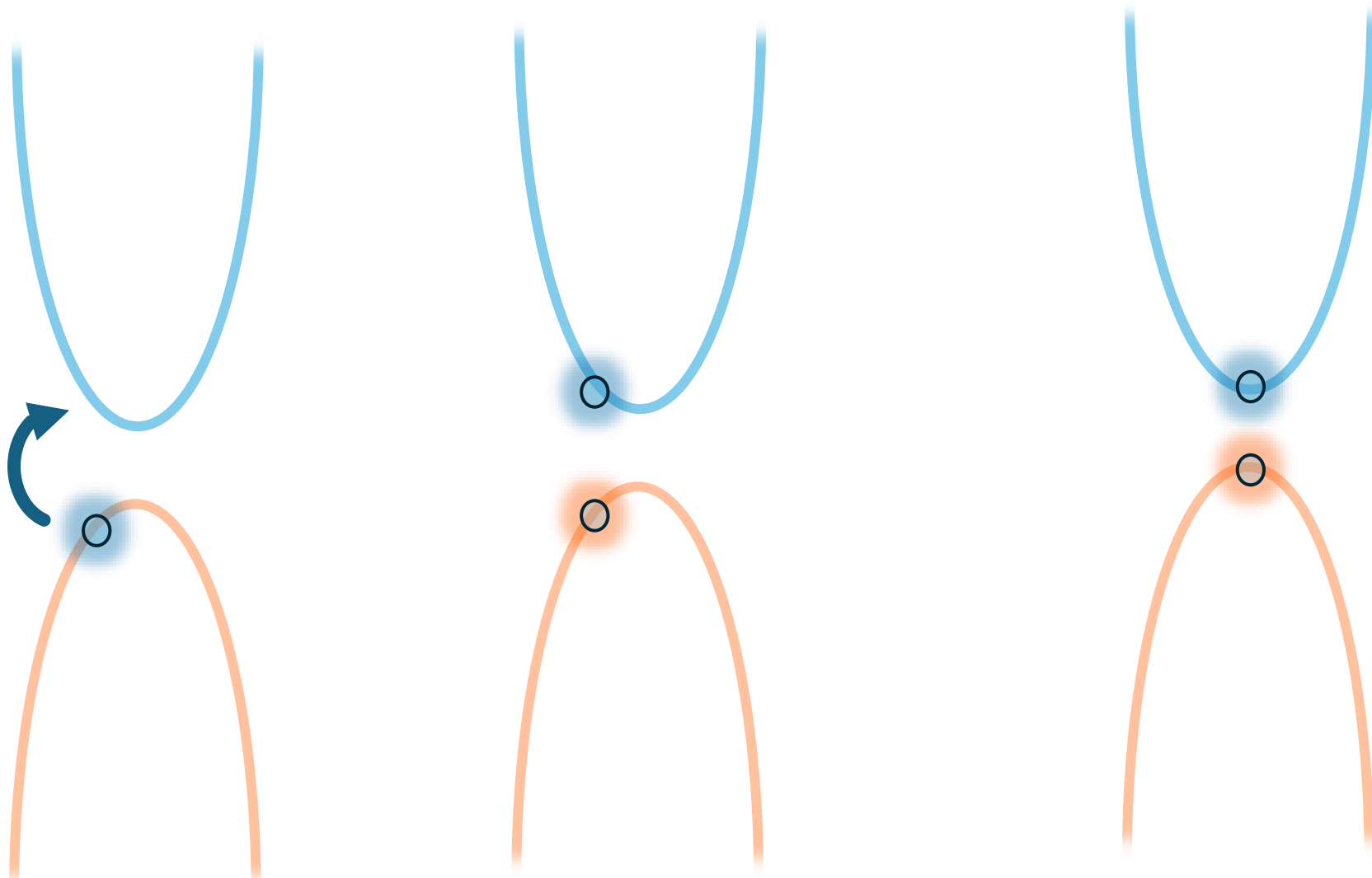
- Intralayer ferromagnetism
- Interlayer antiferromagnetism
 $T_N \approx 140\text{K}$

b	a	c
Easy	Intermediate	Hard

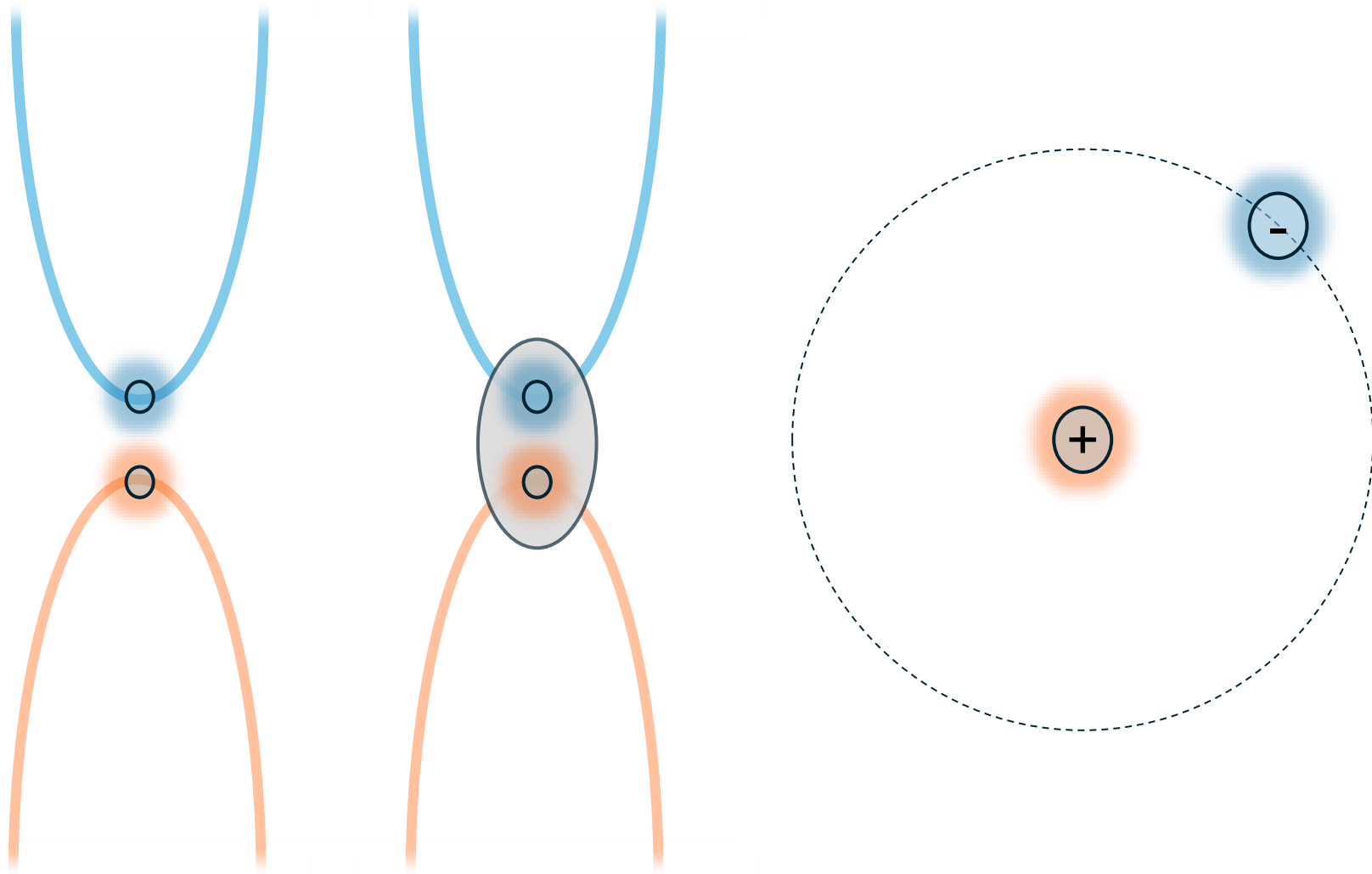
Exciton energy coupled to magnetic order



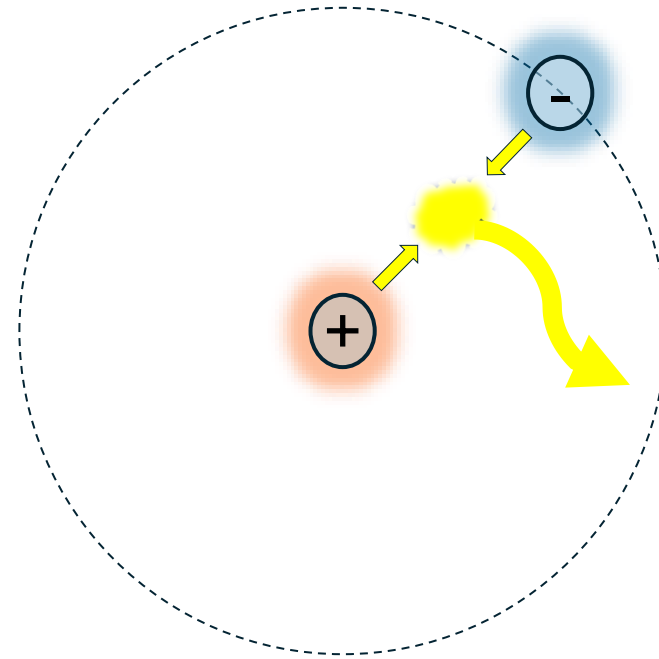
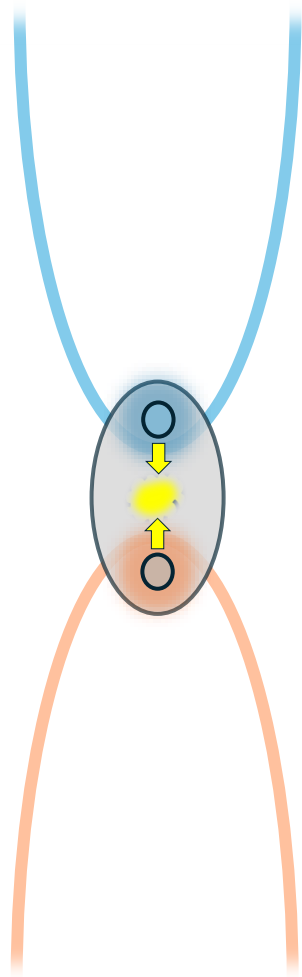
Reminder: excitons



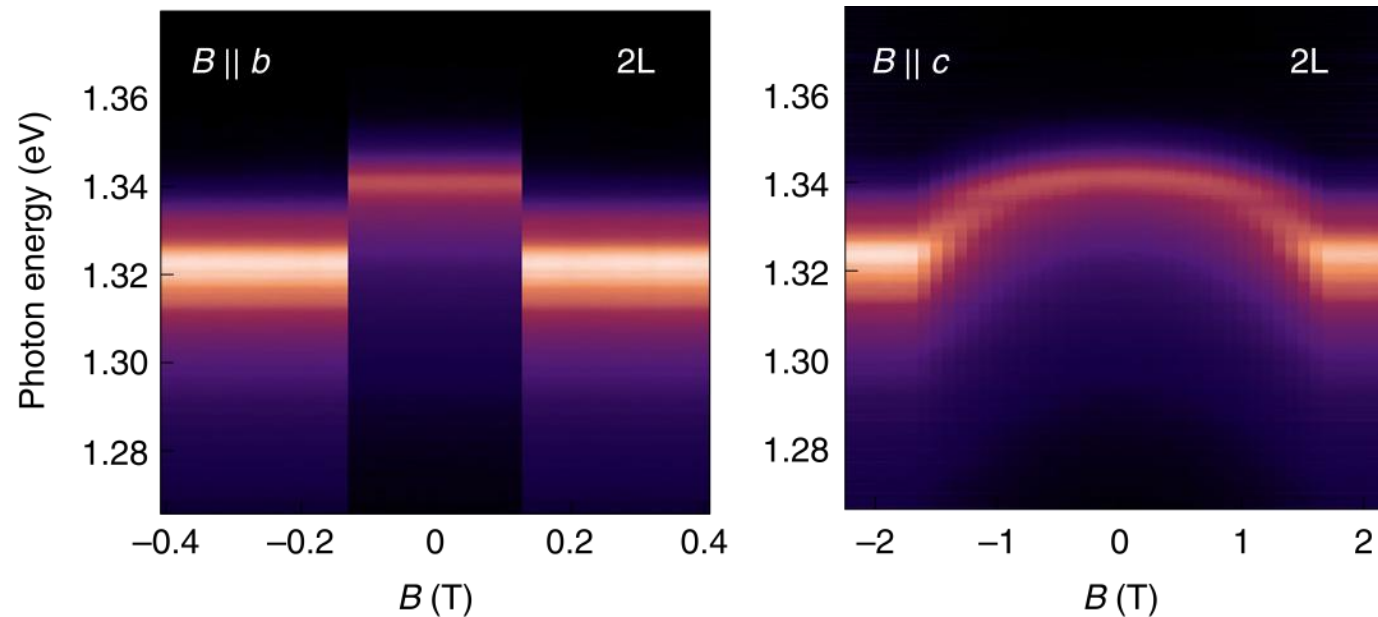
Reminder: excitons



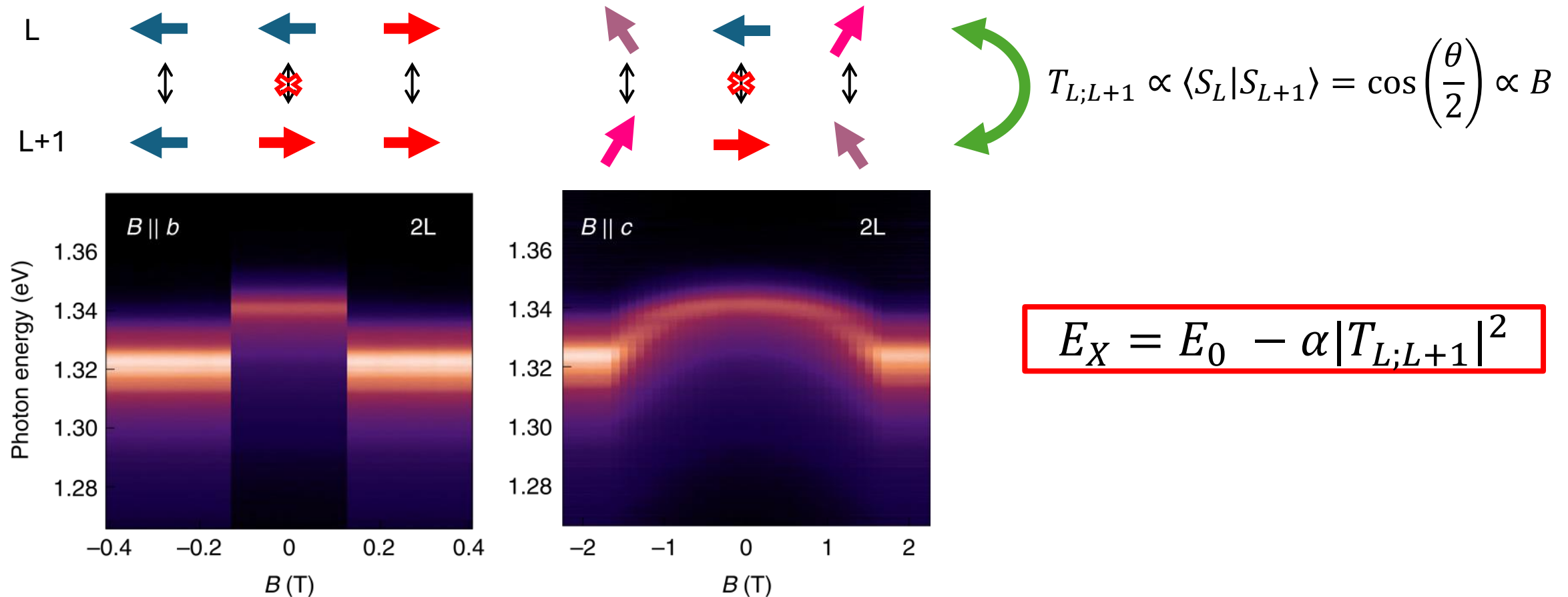
Reminder: excitons



Exciton energy coupled to magnetic order

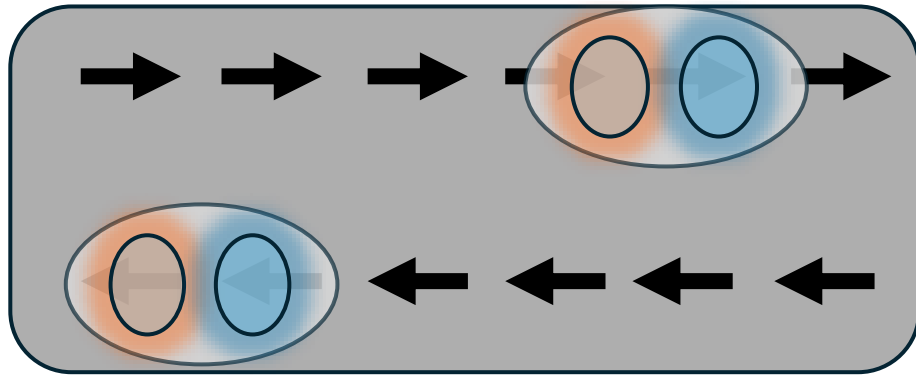


Exciton energy coupled to magnetic order

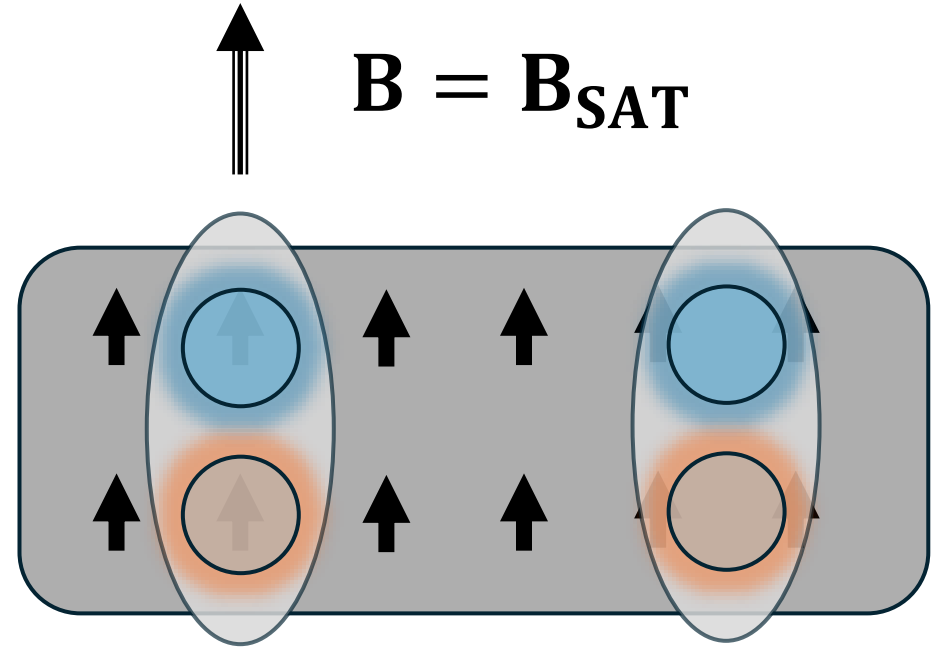


How to verify this?

$$\mathbf{B} = 0$$

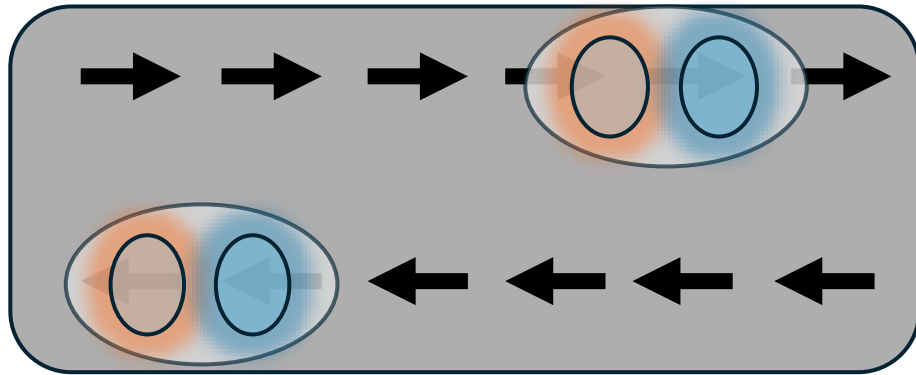


$$\mathbf{B} = \mathbf{B}_{\text{SAT}}$$



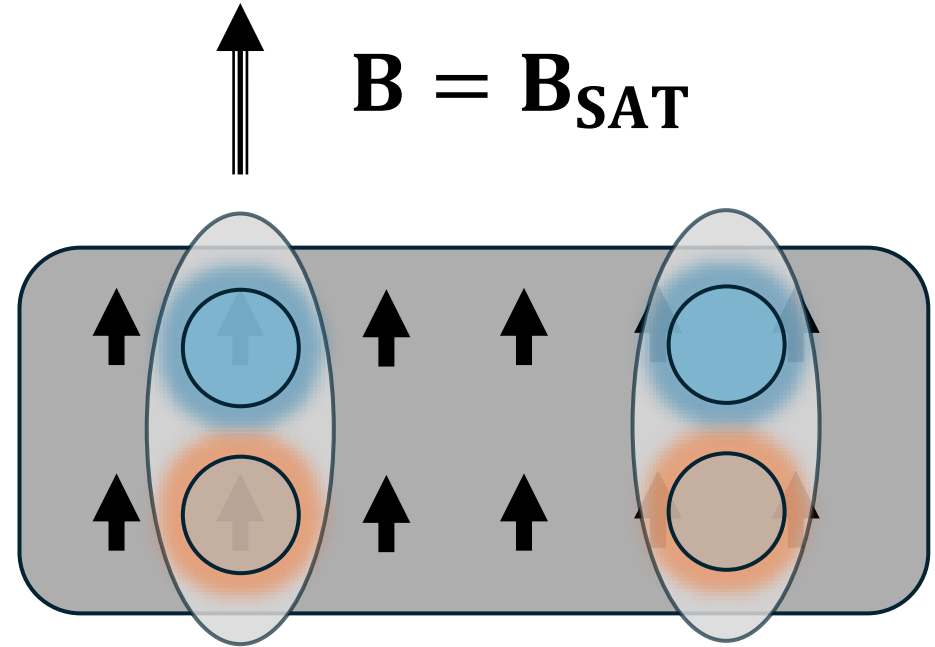
How to verify this?

$$\mathbf{B} = \mathbf{0}$$



Small polarizability

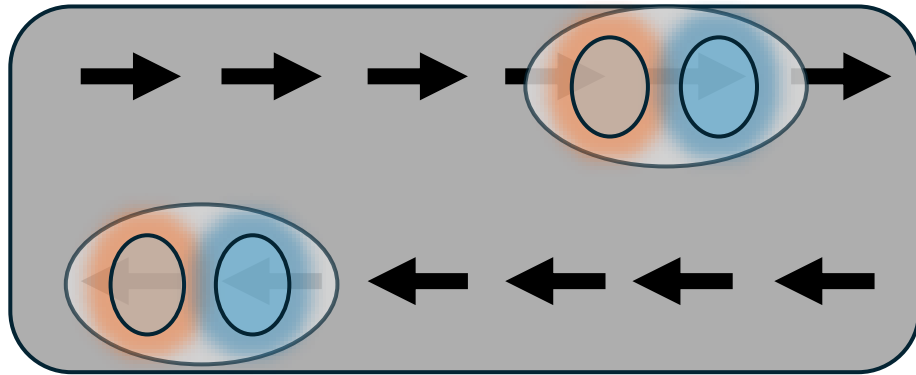
$$\mathbf{B} = \mathbf{B}_{\text{SAT}}$$



Large polarizability

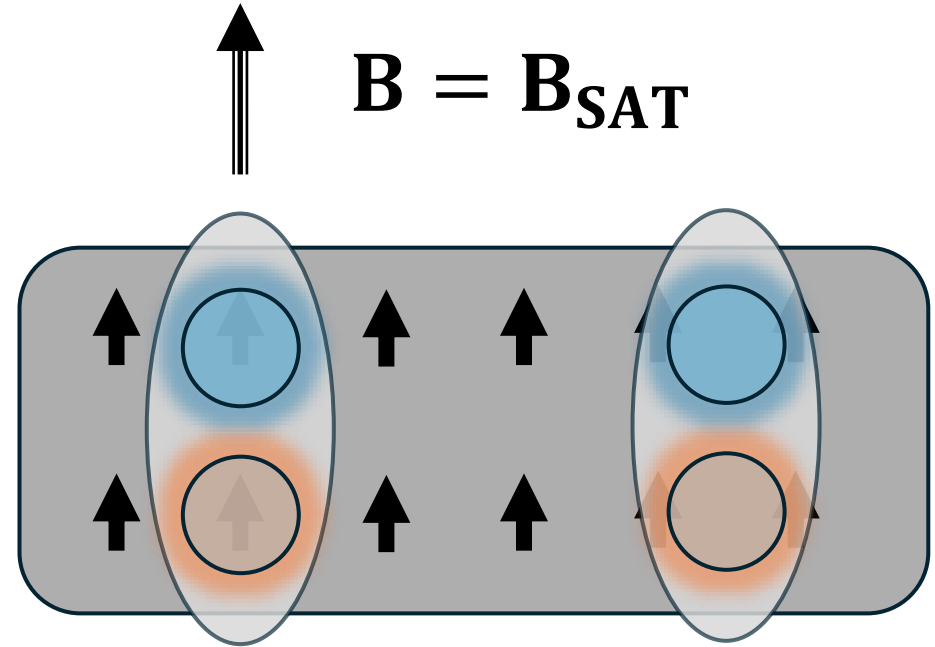
How to verify this?

$$\mathbf{B} = 0$$



Small polarizability

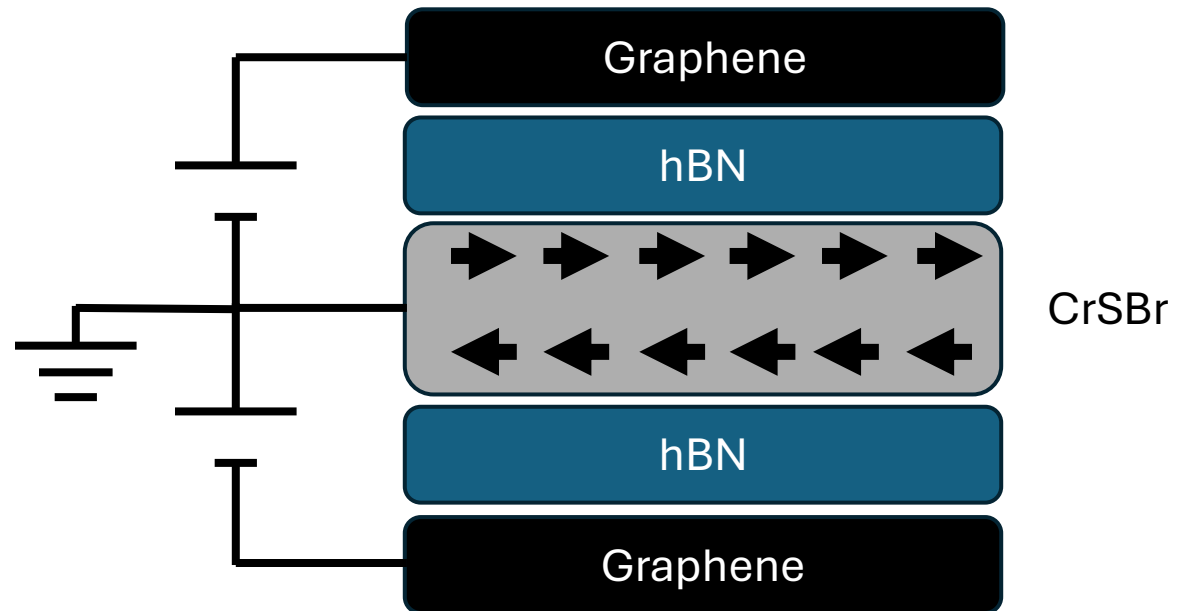
$$\mathbf{B} = \mathbf{B}_{\text{SAT}}$$



Large polarizability

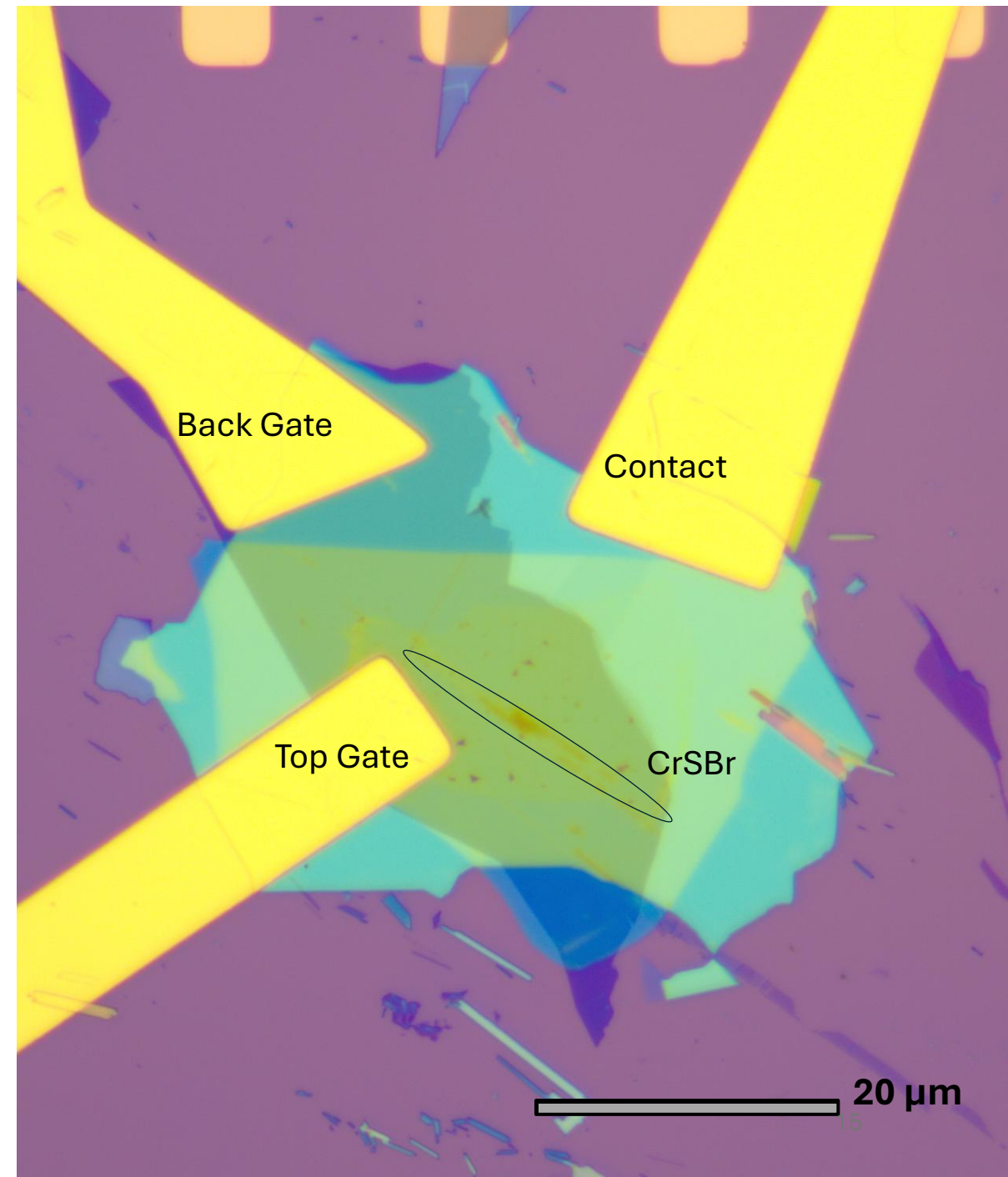
Apply E-field!

With such a device

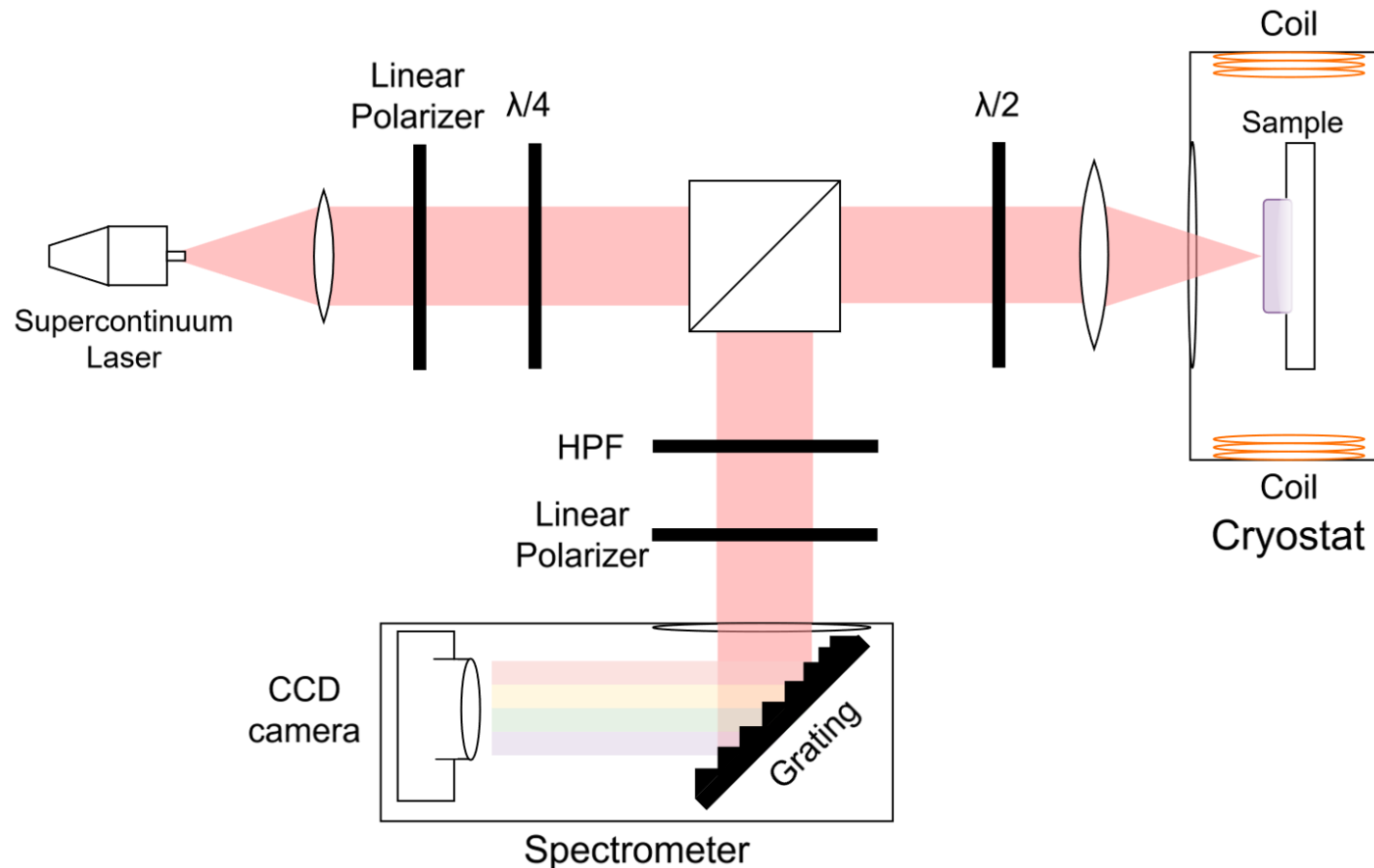


First CrSBr device

- Backgate not working
- Doping possible with contact and top gate

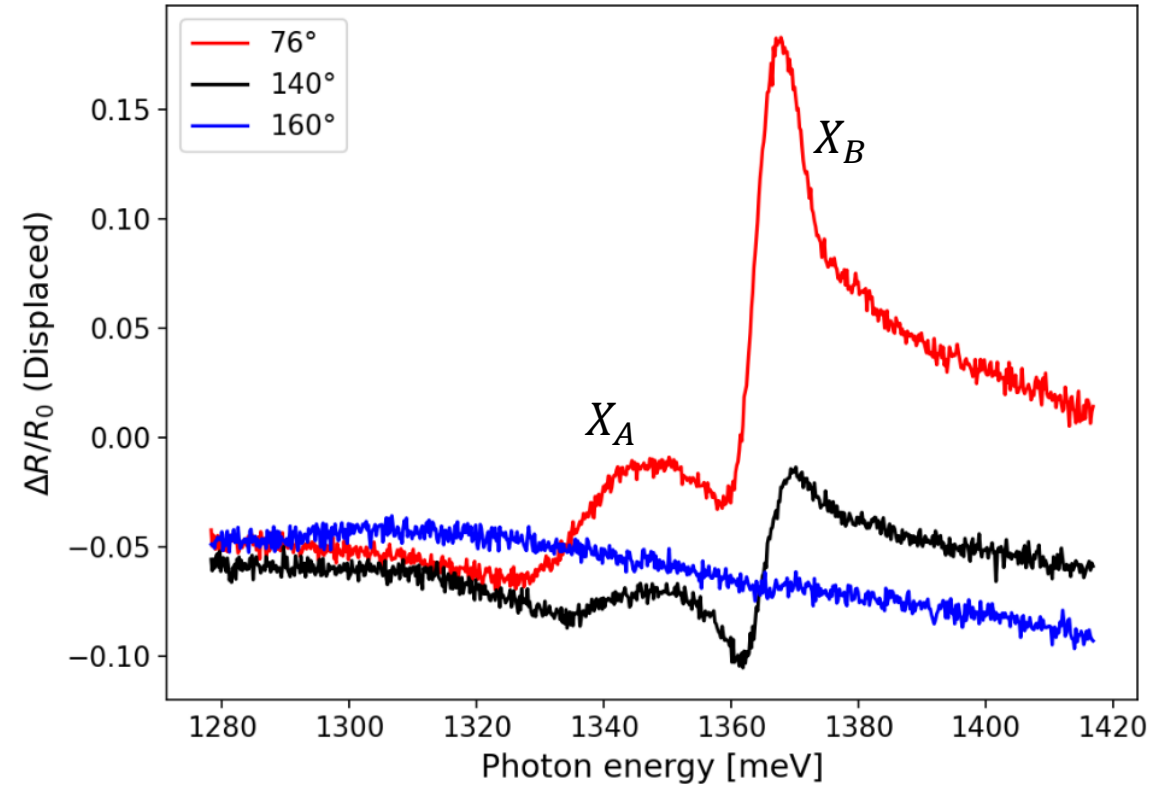
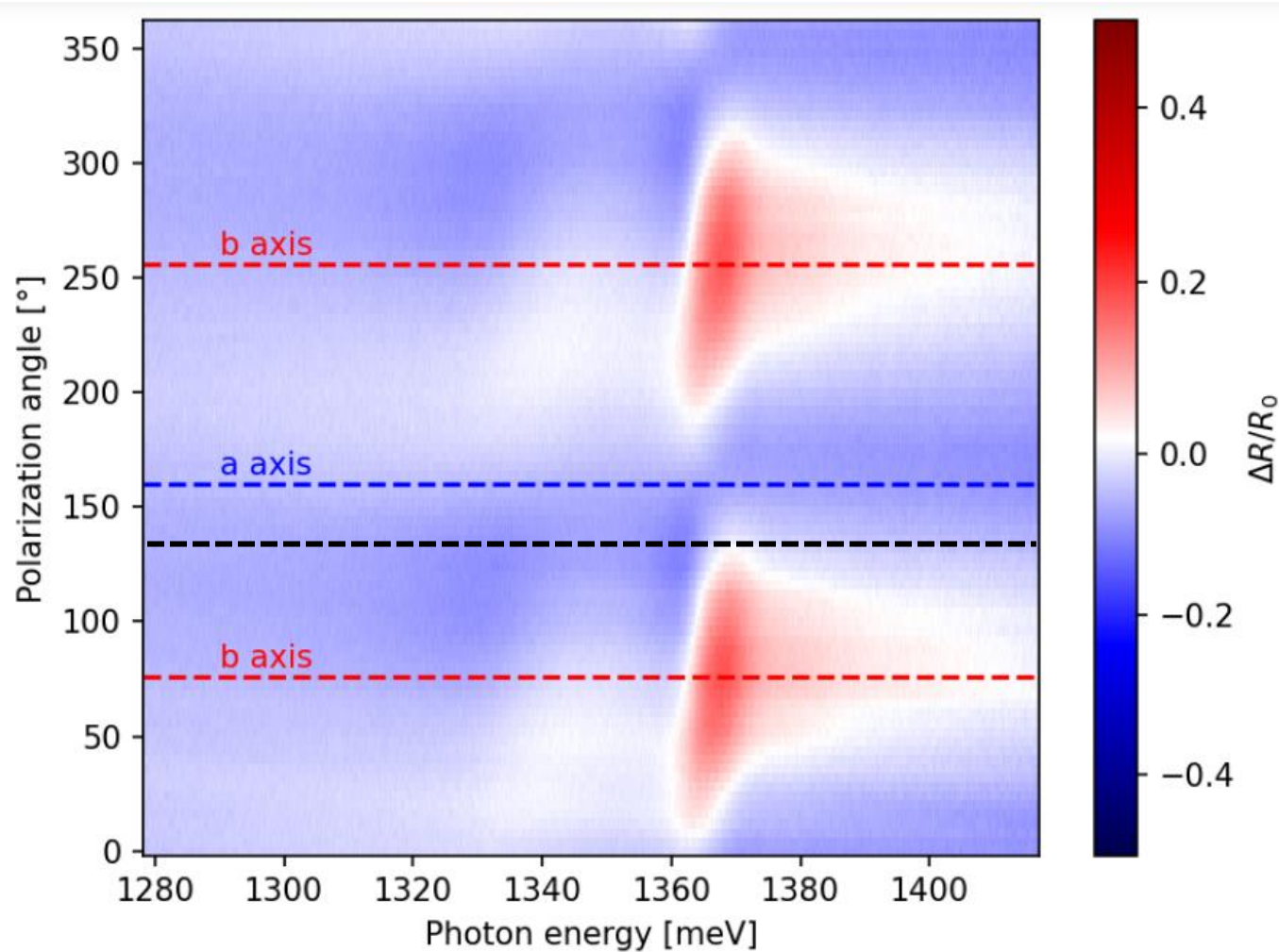


Polarization-Resolved Differential Reflectance Spectroscopy

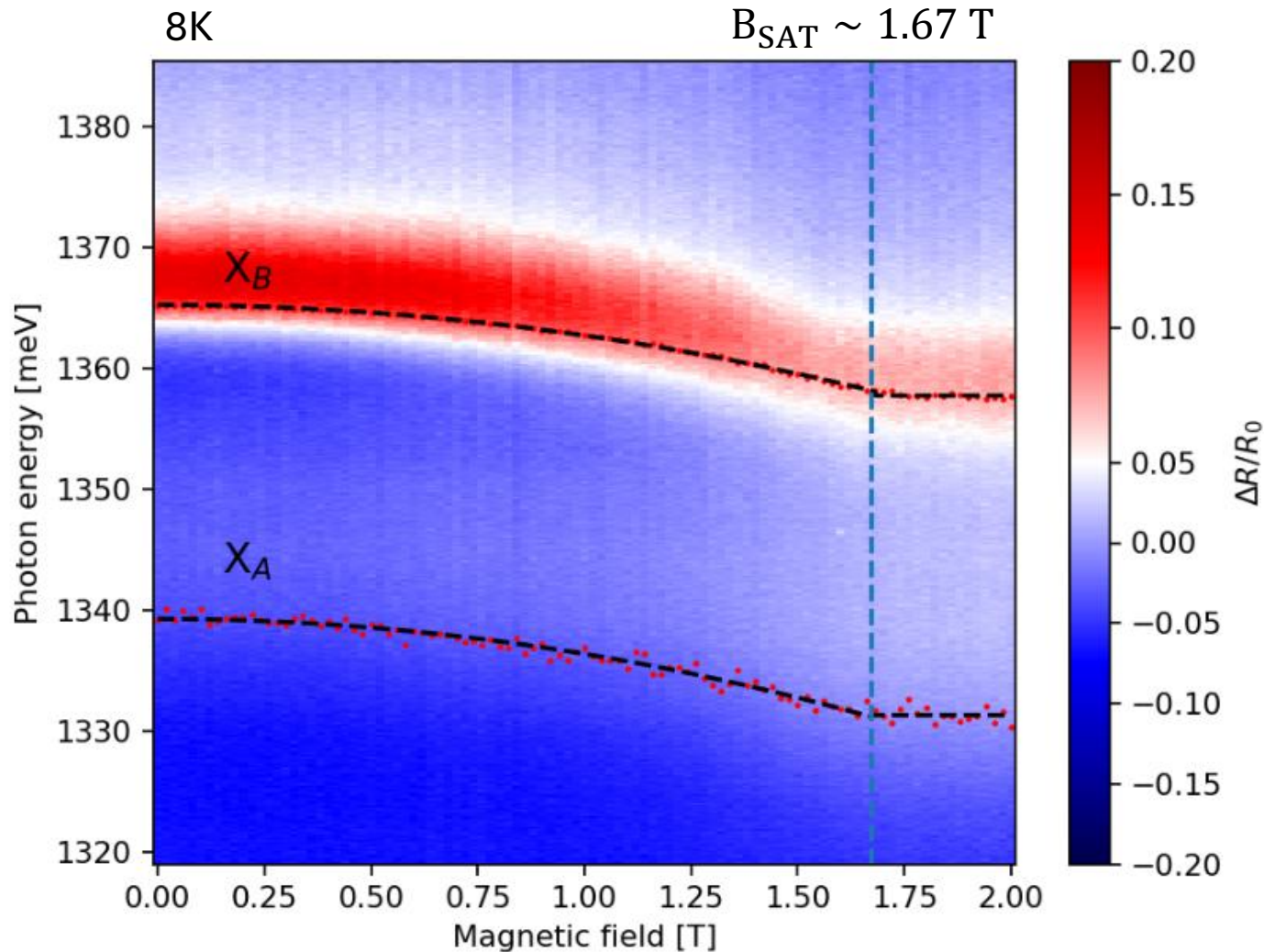


- Measure $\frac{\Delta R}{R_0} \propto \text{Im}(\chi(\omega))$
- Study exciton resonance

Complete linear polarization



Exciton energy vs magnetic field

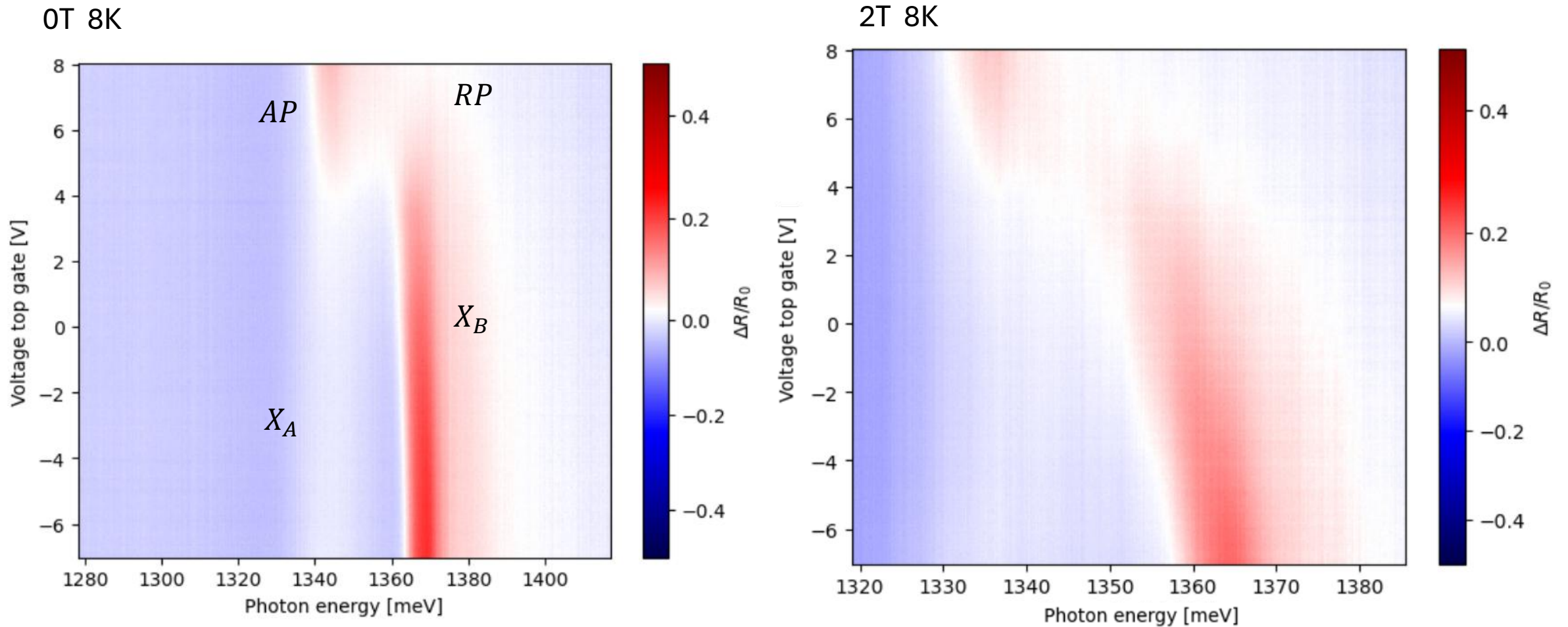


$$E_X = E_0 - \alpha B^2$$

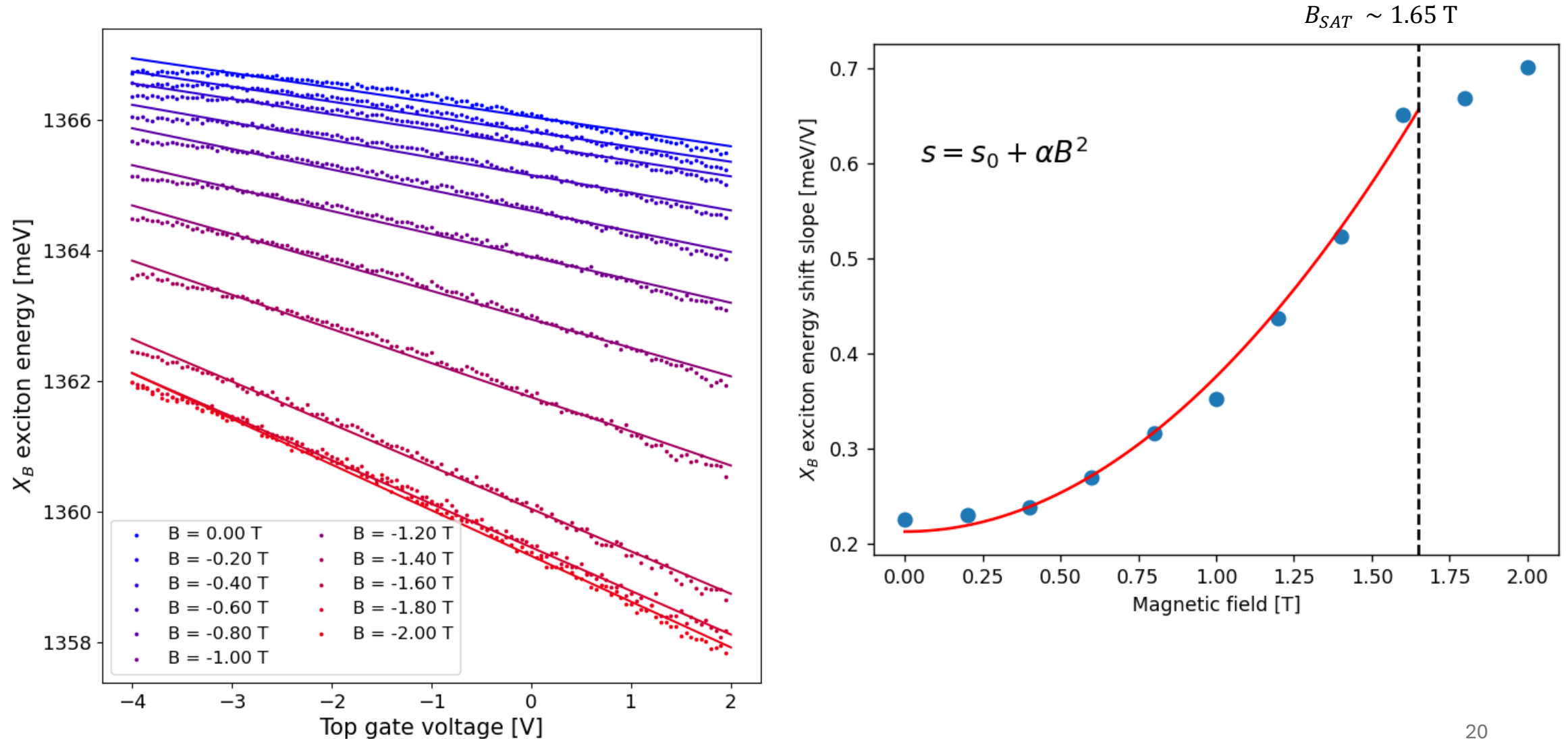
$$\alpha(X_A) \sim 2.9 \text{ meV} \cdot T^{-2}$$

$$\alpha(X_B) \sim 2.5 \text{ meV} \cdot T^{-2}$$

Exciton energy vs top gate voltage

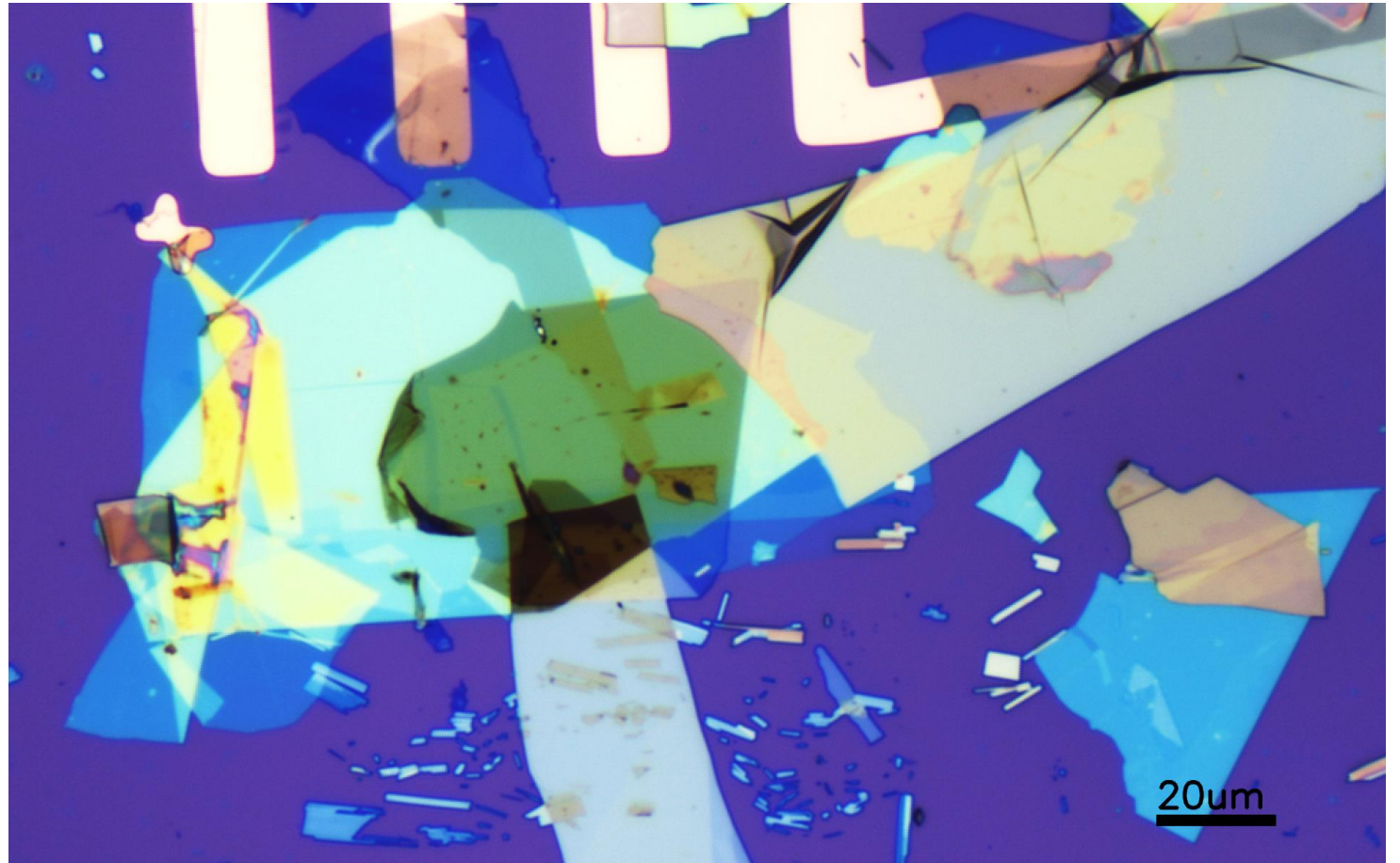


Slope for different magnetic fields

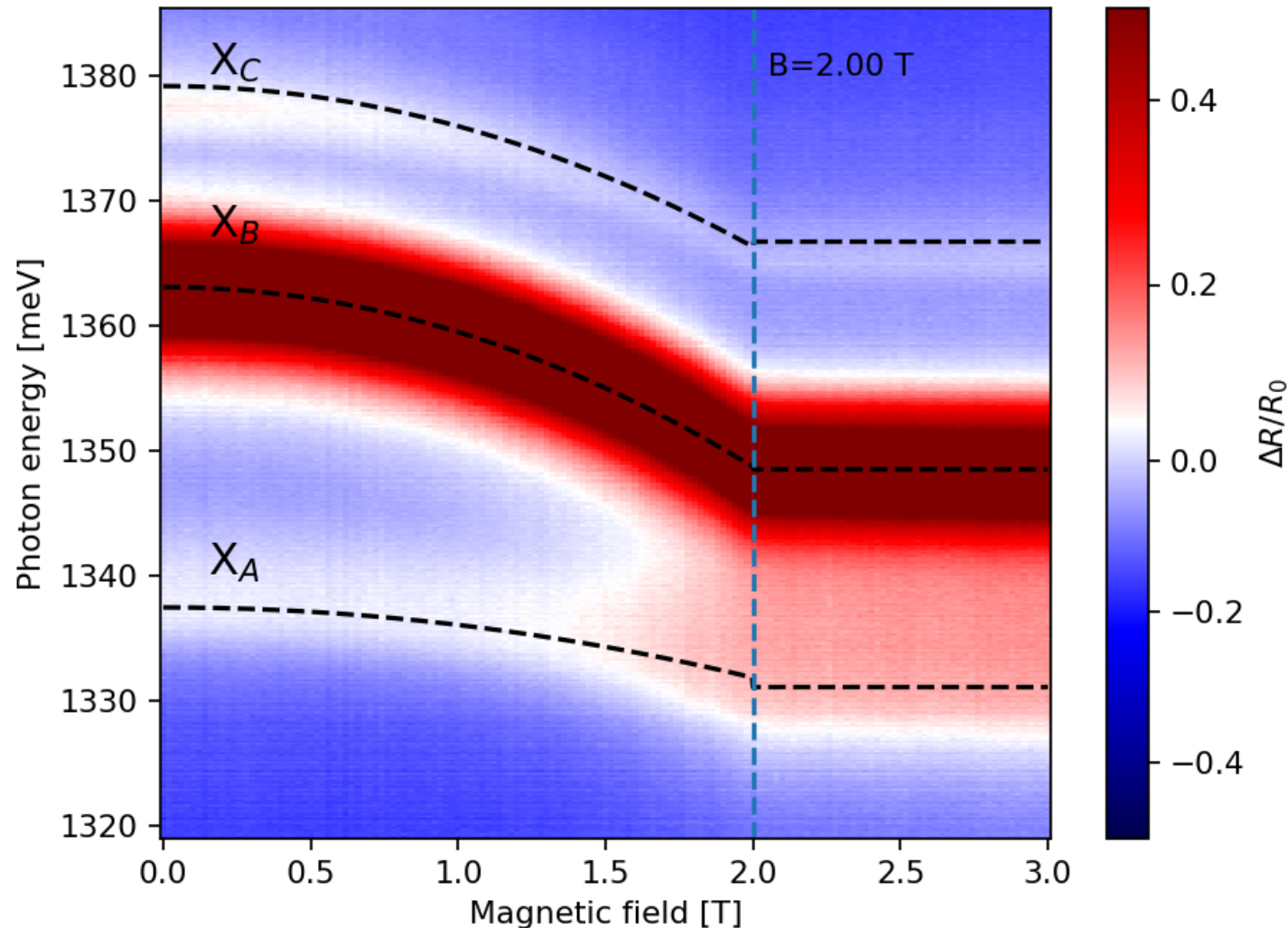


Second device

- 8 nm thick CrSBr
- Multiple graphite patches to avoid lithography



Exciton energy vs magnetic field



$$E_X = E_0 - \alpha B^2$$

First device

$$\alpha(X_A) \sim 2.9 \text{ meV} \cdot T^{-2}$$

$$\alpha(X_B) \sim 2.5 \text{ meV} \cdot T^{-2}$$

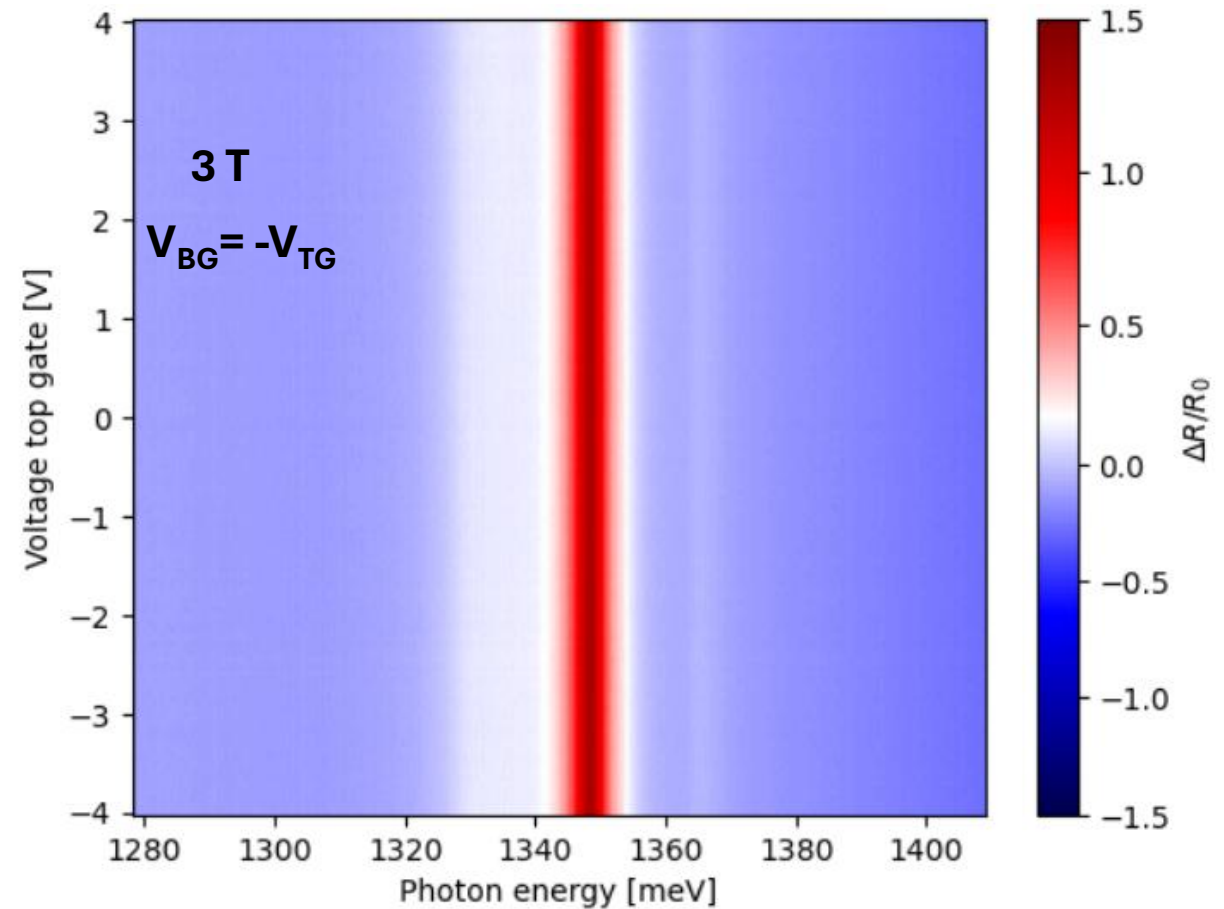
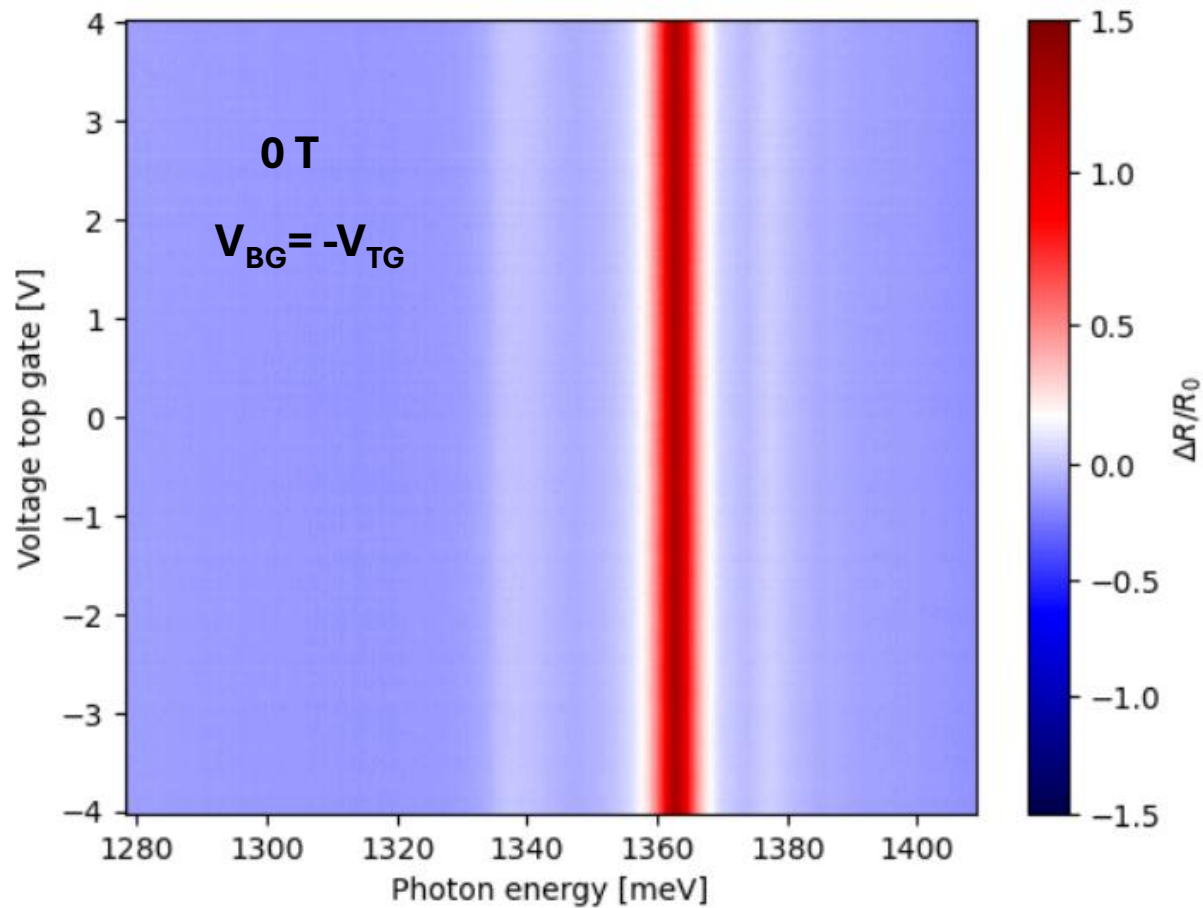
This device

$$\alpha(X_A) \sim 1.4 \text{ meV} \cdot T^{-2}$$

$$\alpha(X_B) \sim 3.6 \text{ meV} \cdot T^{-2}$$

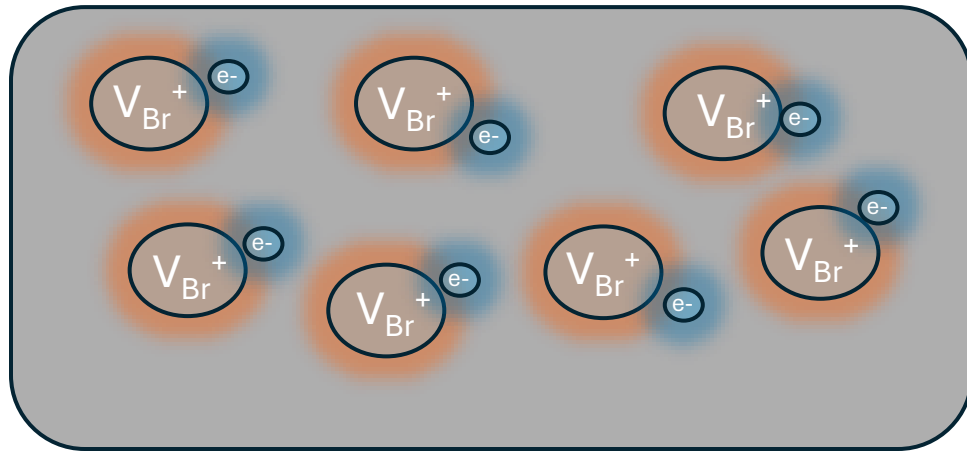
$$\alpha(X_C) \sim 3.2 \text{ meV} \cdot T^{-2}$$

Unfortunately...

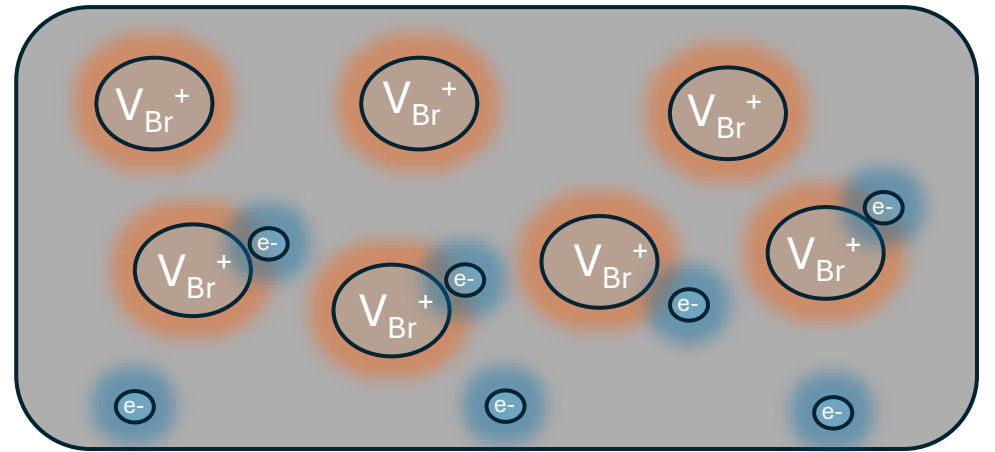


New perspective: screening due to n-doping from vacancies

$E=0$



E



➤ **PL measurements could potentially verify this, but nothing found yet**

Conclusion

- Bilayer device with doping, and promising electric response
- No significant response to electrical field on thick devices
- Electrical control only seems to be possible in the thin flake limit
- Donor-like Bromine vacancies are a possible explanation

Outlook

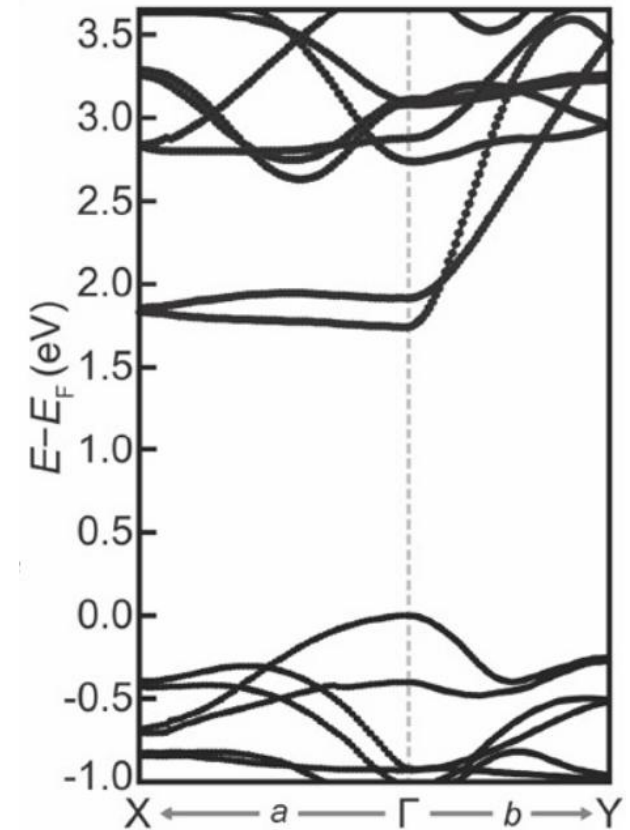
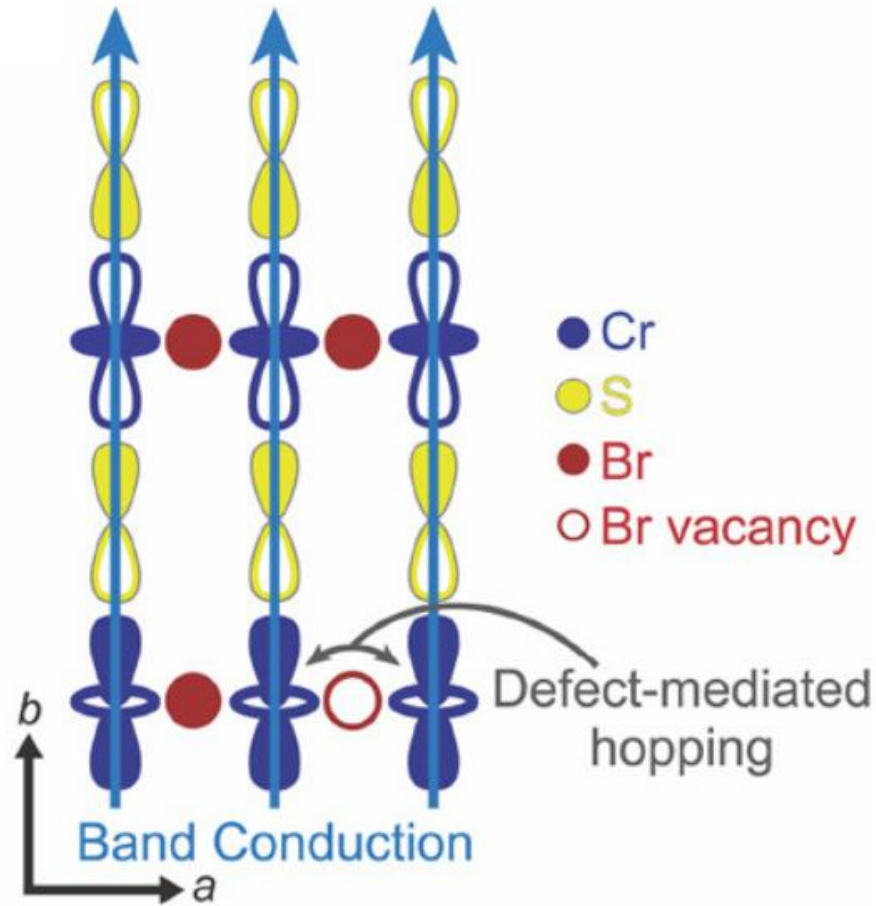
- Understanding the vacancies of this material
- New heterostructures: TMDs, twisted bilayers
- Exploring photonic integration of this material

Questions?

Acknowledgements



Properties of CrSBr: quasi-1D

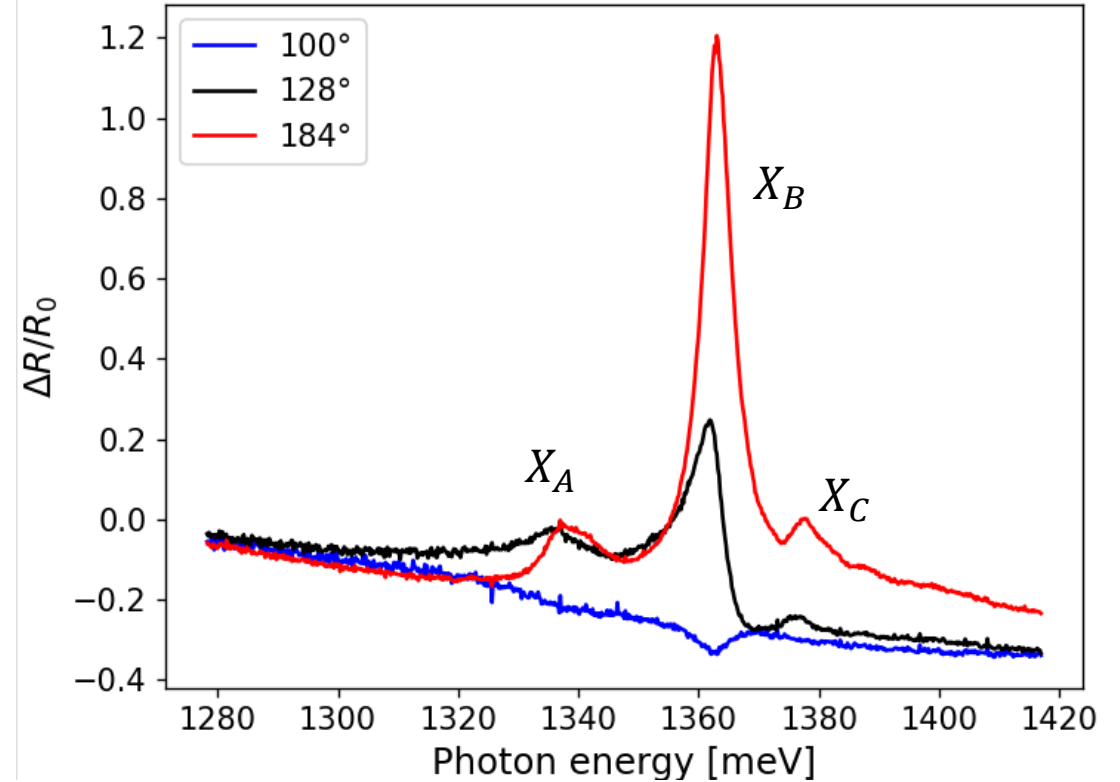
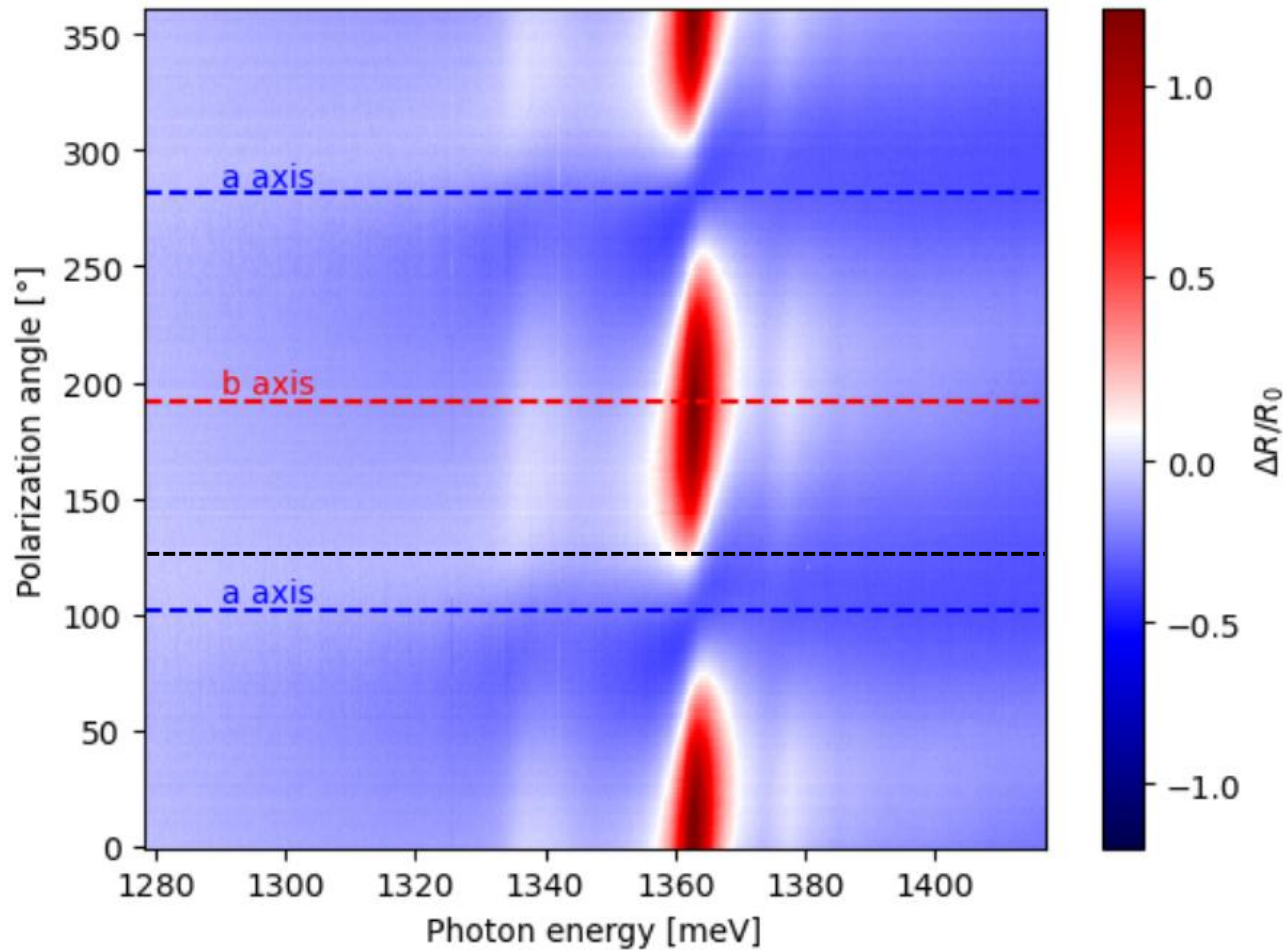


$$m_x^e / m_y^e \sim 50$$

$$m_x^h / m_y^h \sim 6$$

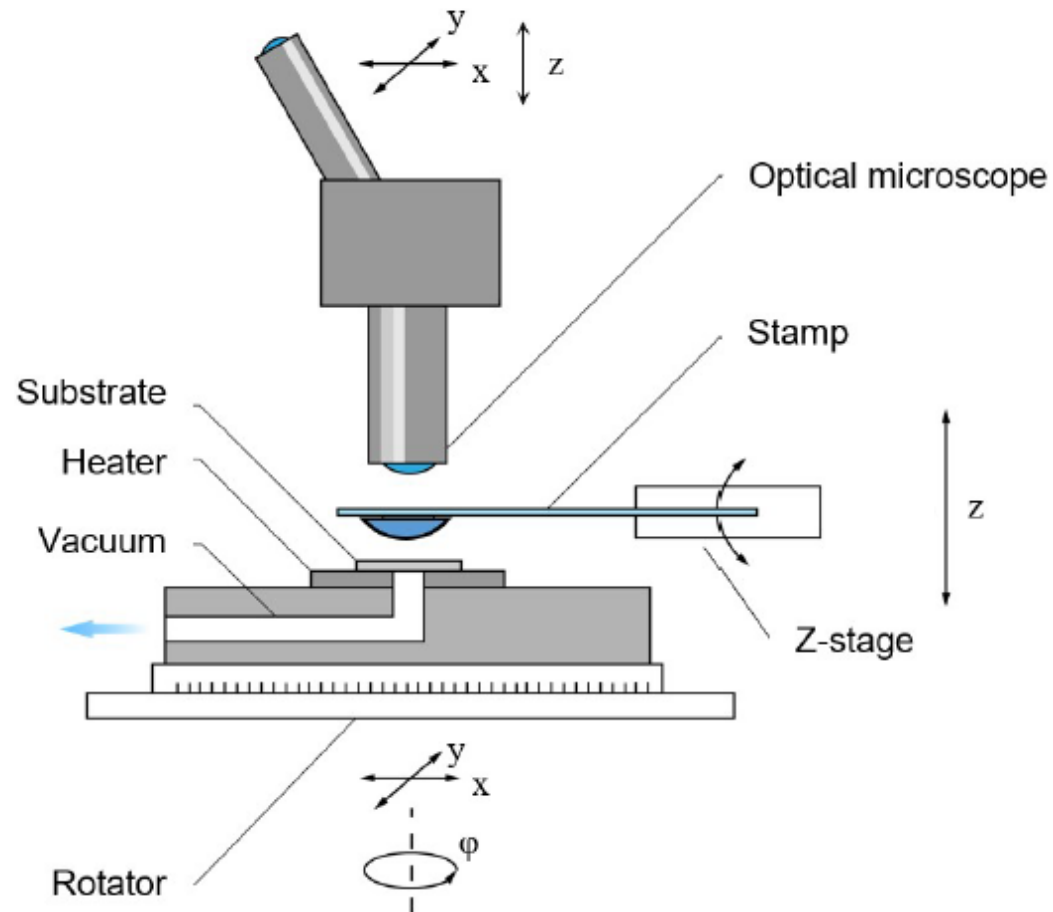
Complete linear polarization

0T 8K

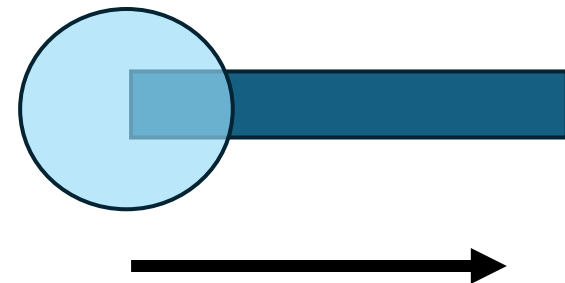


But first... fabrication!

Stacking setup



- PC on PDMS polymer stamp
- $70 \rightarrow 140^{\circ}\text{C}$
- PC front along a-axis (long axis)



Temperature induced structural changes

Volatility of atomic species

- Air sensitivity of monolayers
- Up to $7 \times 10^{13} \text{ cm}^{-2}$ Bromine surface defects
- Increased surface roughness

Decreased
top adhesion



Increased surface conformation

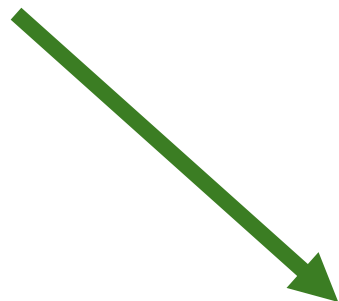
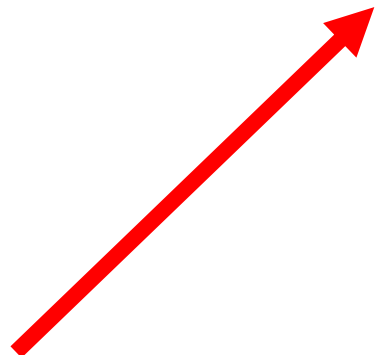
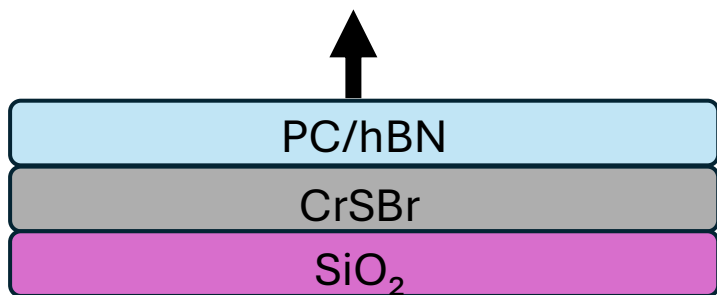
- Effect observed in graphene

Increased
bot adhesion



Covalent bond formation

- SiO_2 surface hydroxyl groups tend to form covalent bonds with Bromine atoms

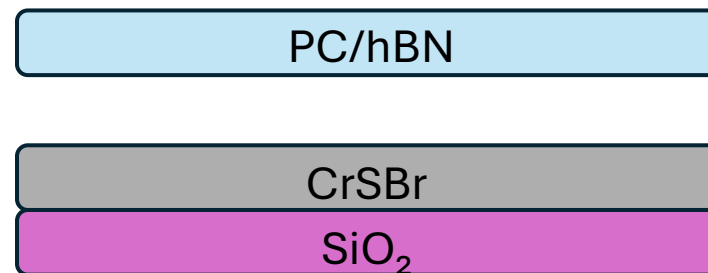


Cohesion failure



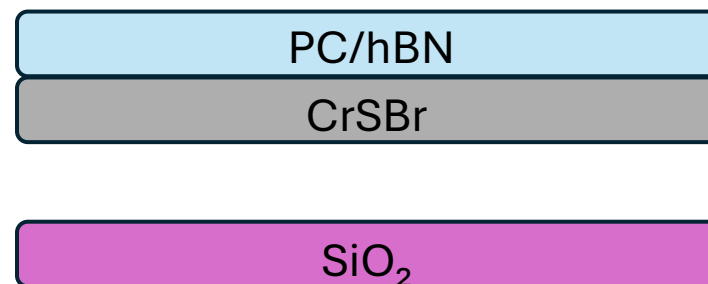
Torn flake

Top adhesion failure



Pick-up failure

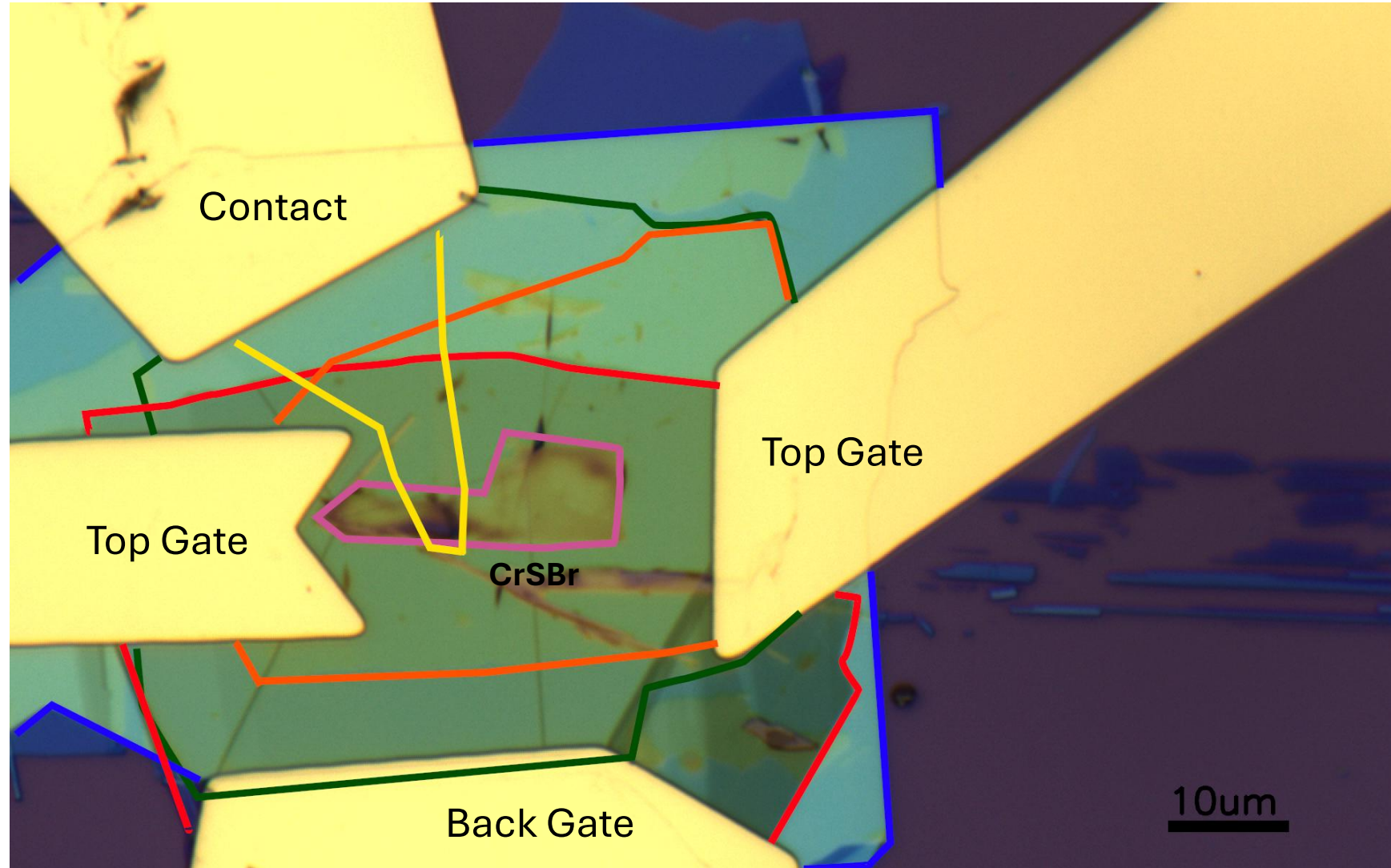
Bottom adhesion failure

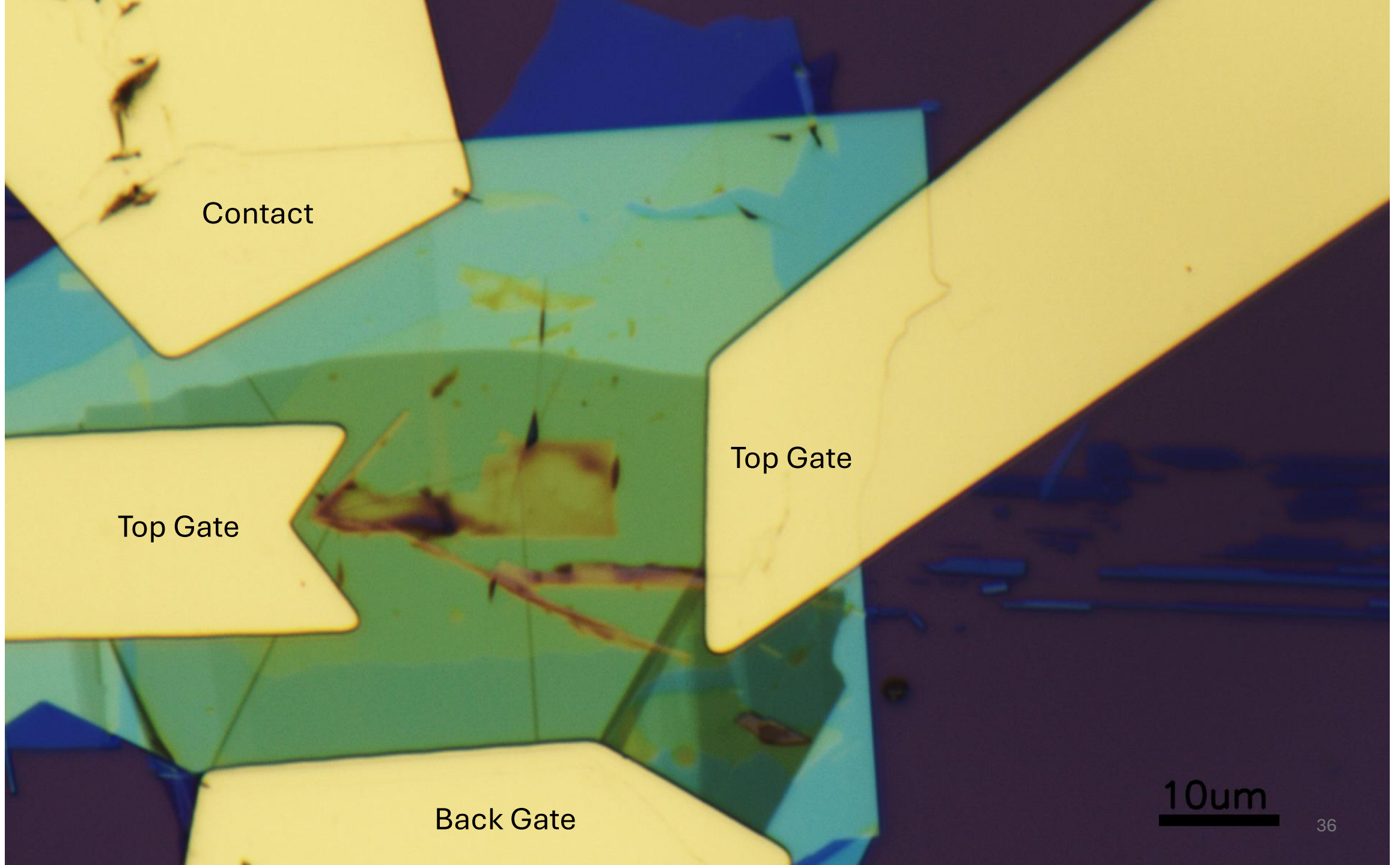


Pick-up success

Third device

- 9 nm CrSBr





Contact

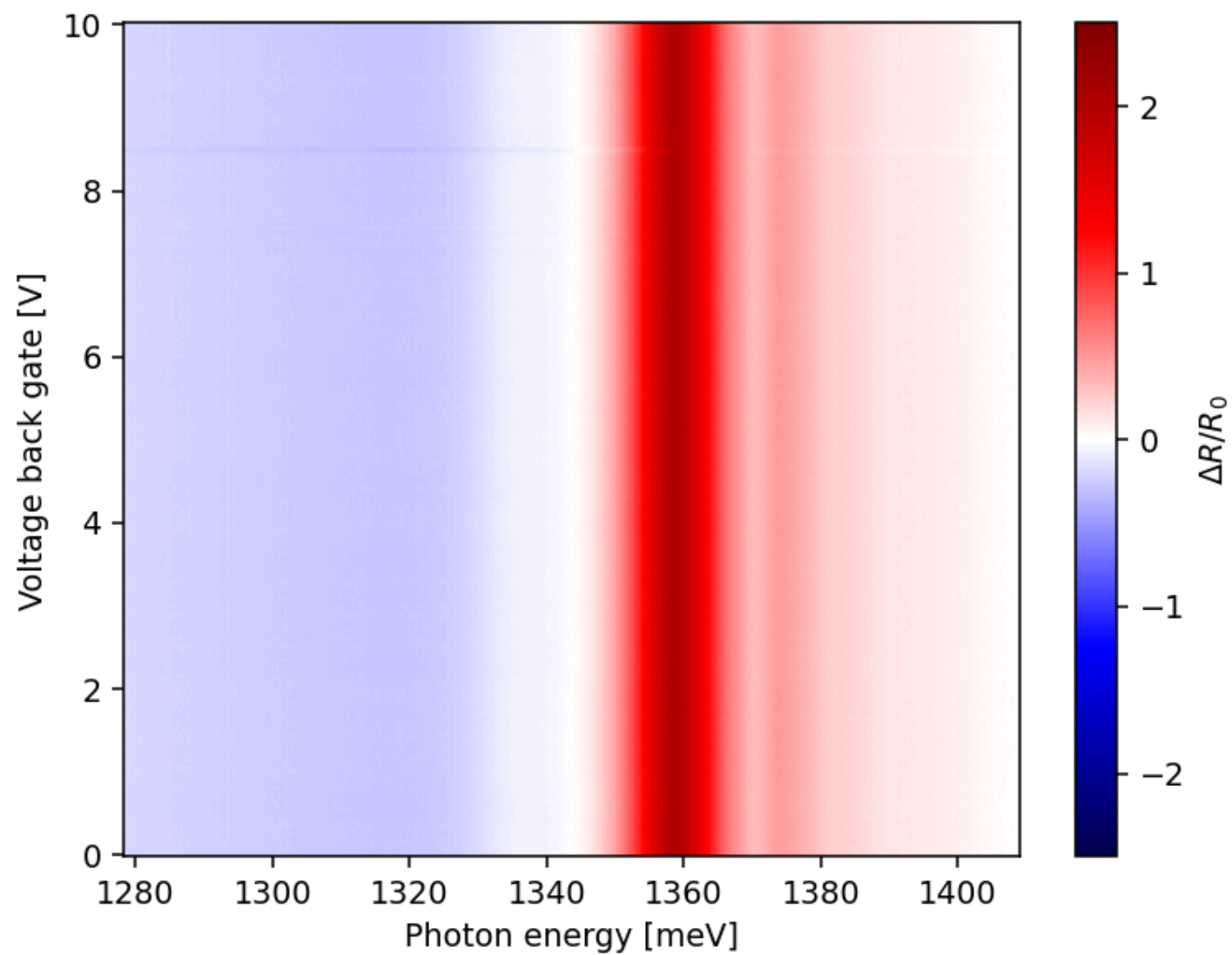
Top Gate

Top Gate

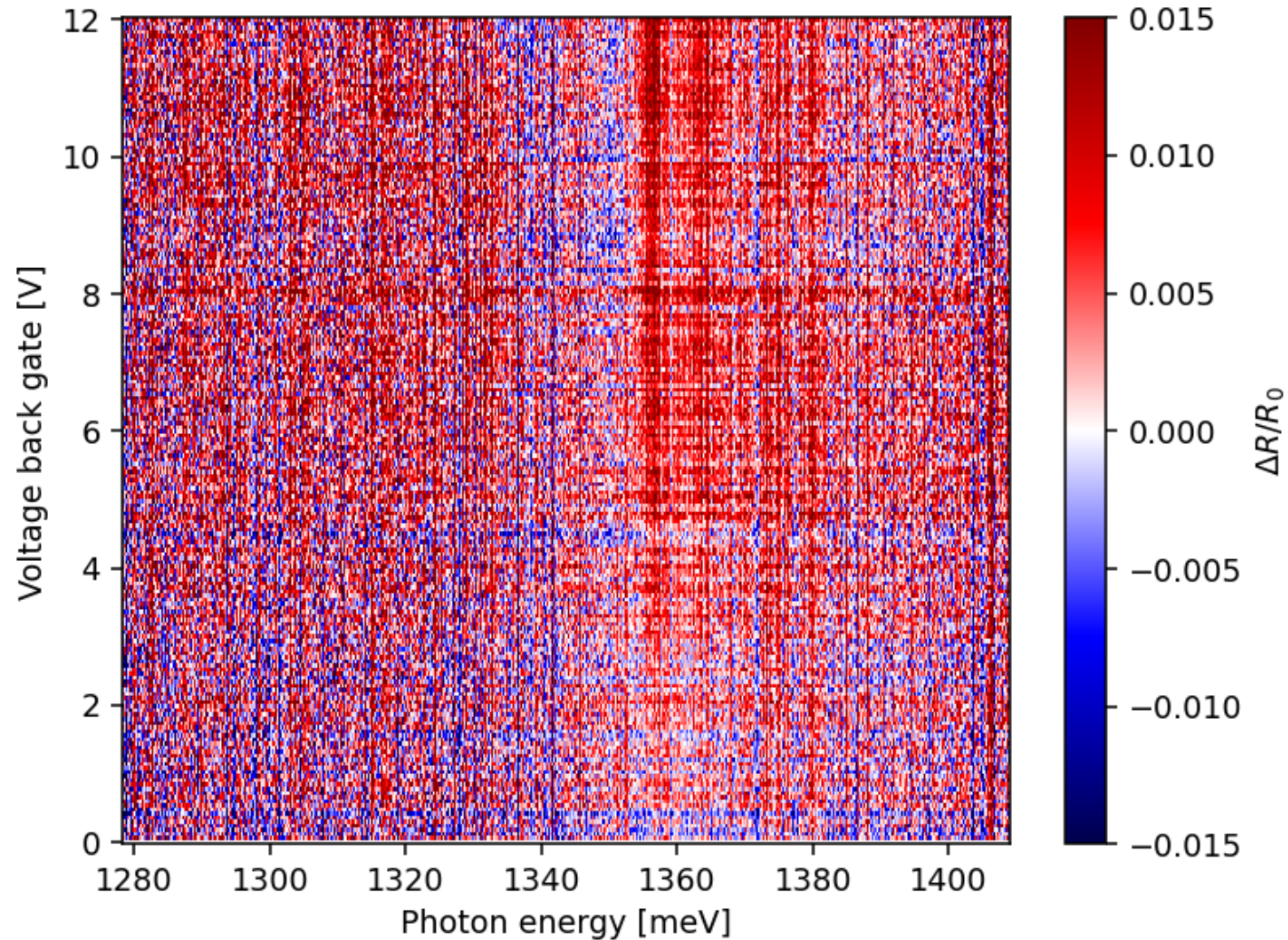
Back Gate

10um

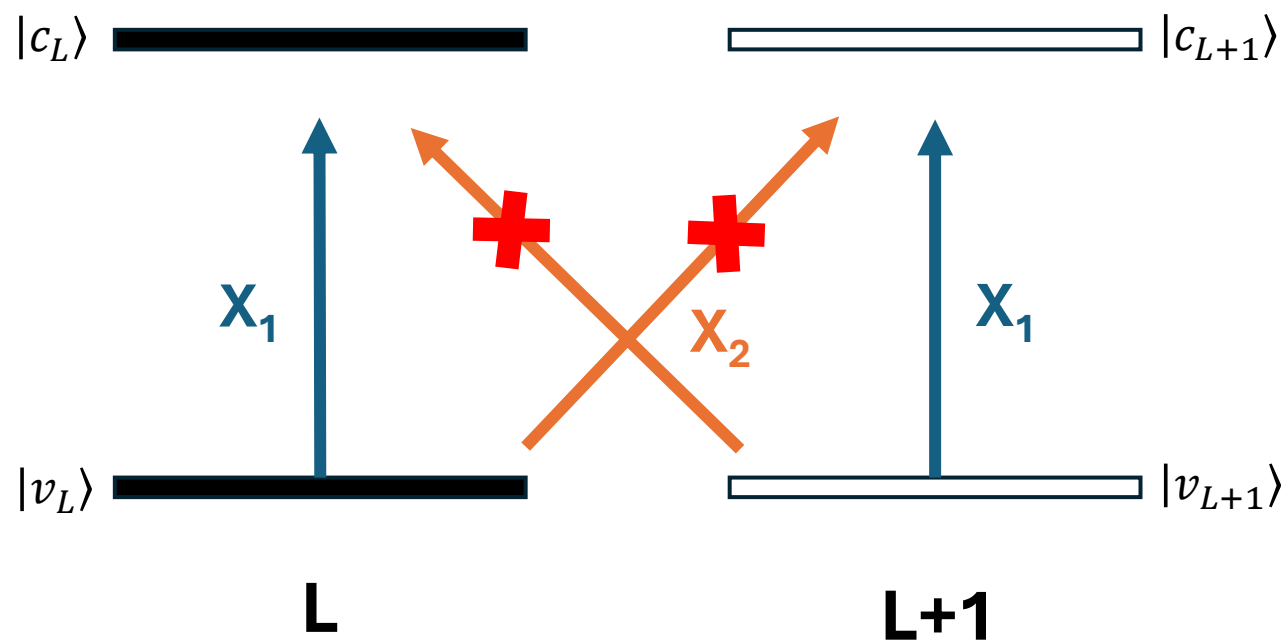
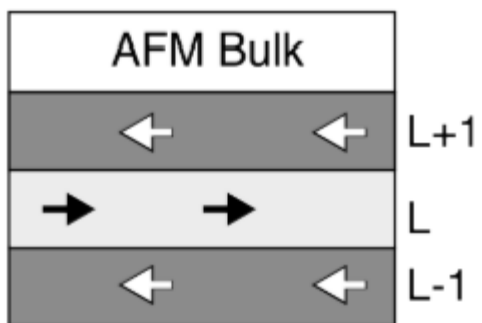
Again...

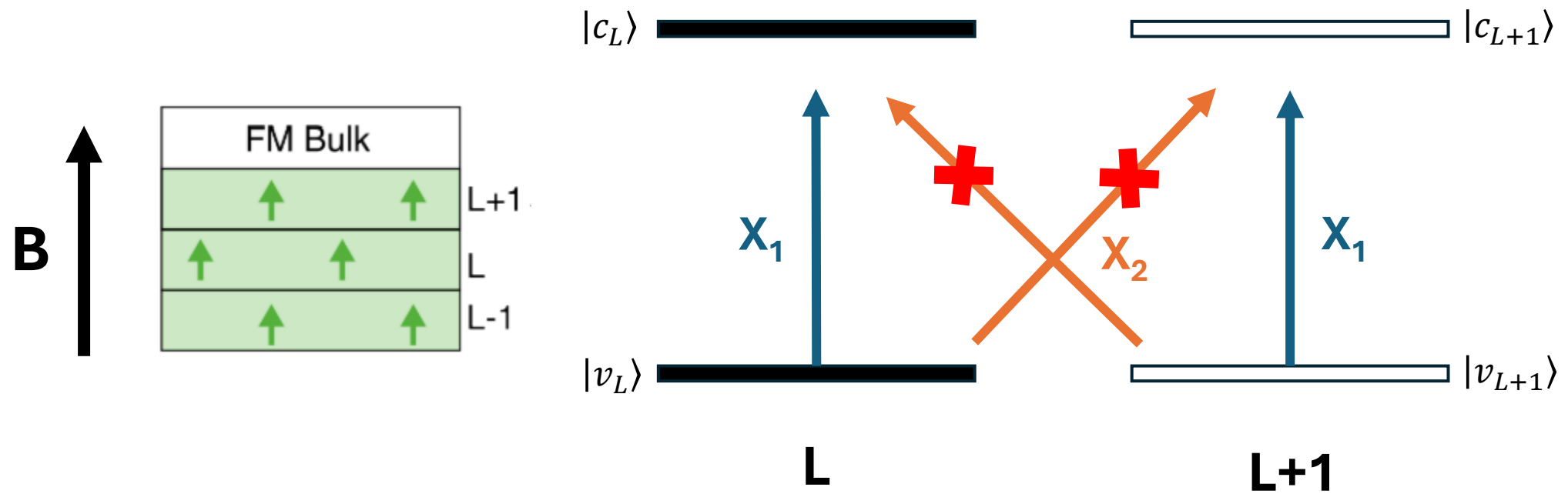


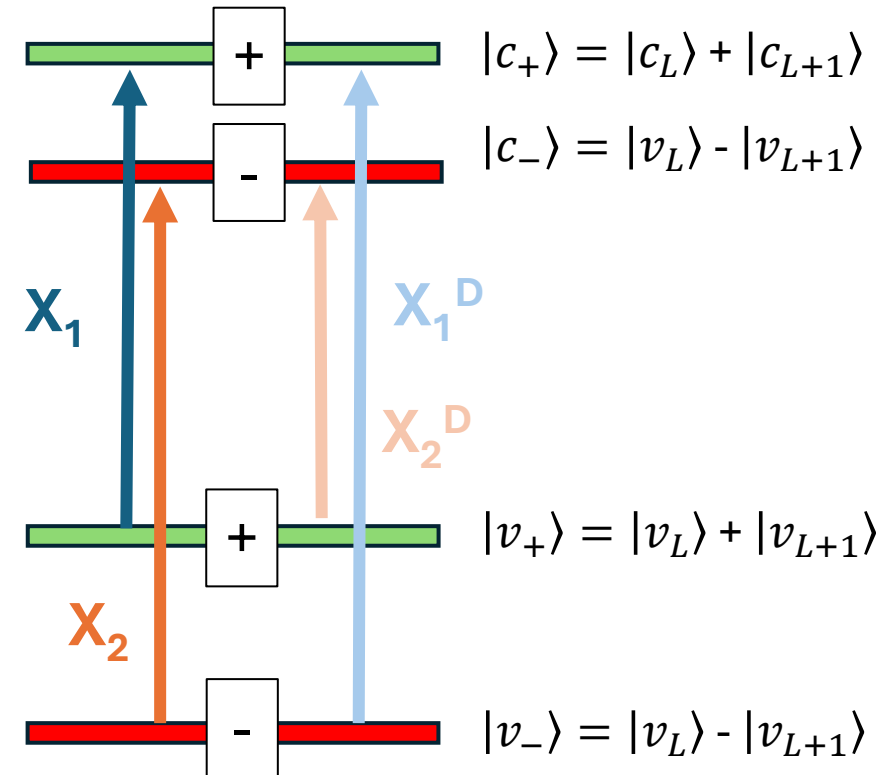
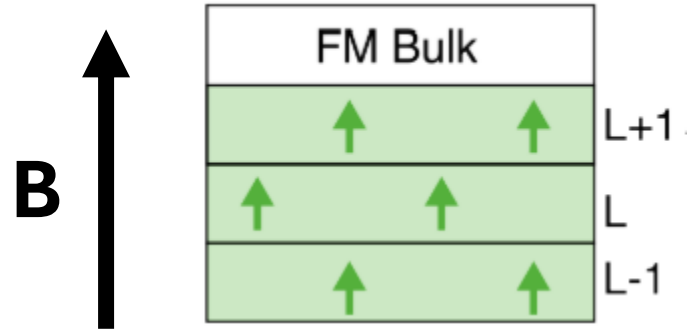
But...



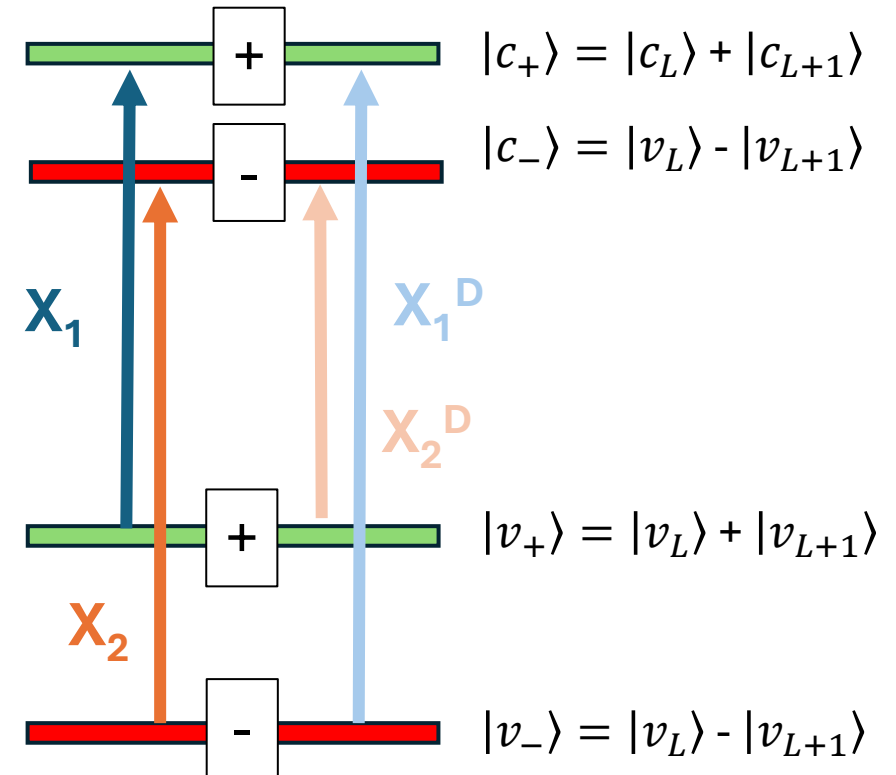
$$\frac{\frac{\Delta R}{R_0}(2L)}{\frac{\Delta R}{R_0}(9\text{nm})} \sim 0.02$$





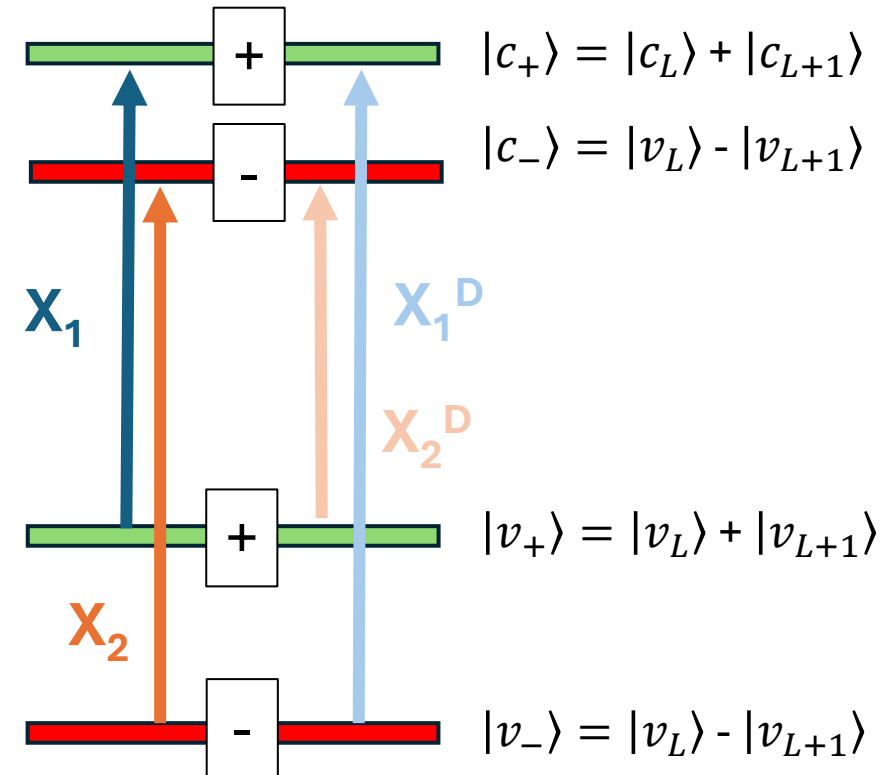


$$H_{\mathbf{k}}^{\text{el}}(B) = \begin{pmatrix} E_{n\mathbf{k}} & t_{n\mathbf{k}}B \\ t_{n\mathbf{k}}B & E_{n\mathbf{k}} \end{pmatrix}$$



$$H_{\mathbf{k}}^{\text{el}}(B) = \begin{pmatrix} E_{n\mathbf{k}} & t_{n\mathbf{k}}B \\ t_{n\mathbf{k}}B & E_{n\mathbf{k}} \end{pmatrix}$$

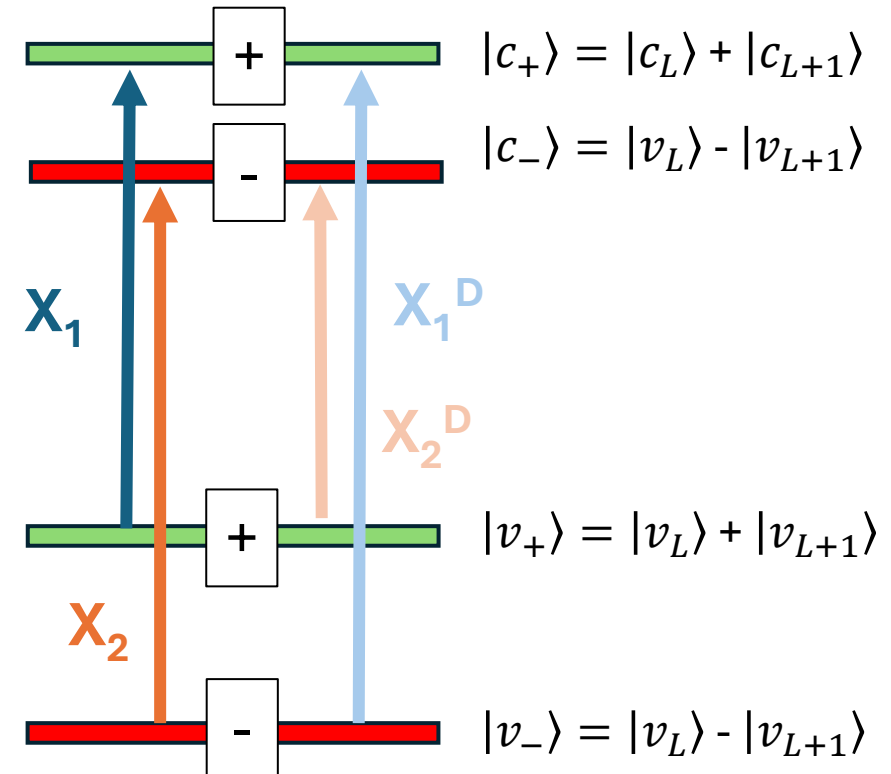
 Eigenvalues



$$H_{\mathbf{k}}^{\text{el}}(B) = \begin{pmatrix} E_{n\mathbf{k}} & t_{n\mathbf{k}}B \\ t_{n\mathbf{k}}B & E_{n\mathbf{k}} \end{pmatrix}$$

 Eigenvalues

$$E_{n\mathbf{k},\pm} = E_{n\mathbf{k}} \pm t_{n\mathbf{k}}B$$



In the exciton basis...

$$H(B) = \begin{bmatrix} E_g + tB + V_{eh} & 0 \\ 0 & E_g - tB + V_{eh} \end{bmatrix}$$



Interaction

$$H(B) = \begin{bmatrix} E_g + tB + V_{eh} & V_I \\ V_I & E_g - tB + V_{eh} \end{bmatrix}$$

In the exciton basis...

$$H(B) = \begin{bmatrix} E_g + tB + V_{eh} & V_I \\ V_I & E_g - tB + V_{eh} \end{bmatrix}$$



Diagonalization

$$\lambda_{+,-} = E_g + V_{eh} \pm \sqrt{(tB)^2 + V_I^2}$$

**Dominant B^2 contribution for
strong enough interaction**

hBN thicknesses

- CrSBr1:
 - Top hBN: 21.9 nm
 - Bottom hBN: 38.3 nm
- CrSBr5
 - Top hBN: 27.9 nm
 - Bottom hBN: 25.5 nm
- CrSBr8
 - Top hBN: 19 nm
 - Bottom hBN: 51.5 nm